

Sacha:

Stanford Carbon Nanotube Controlled Handshaking Robot

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G. Gielen, H.-S. P. Wong, S. Mitra



Stanford University



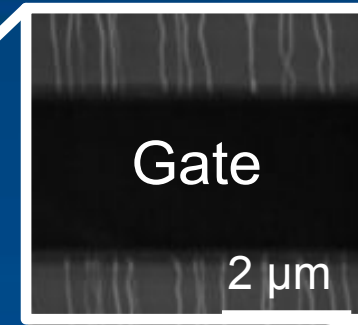
KU Leuven

Carbon Nanotube FET (CNFET)



Diameter $\sim 1.2\text{nm}$

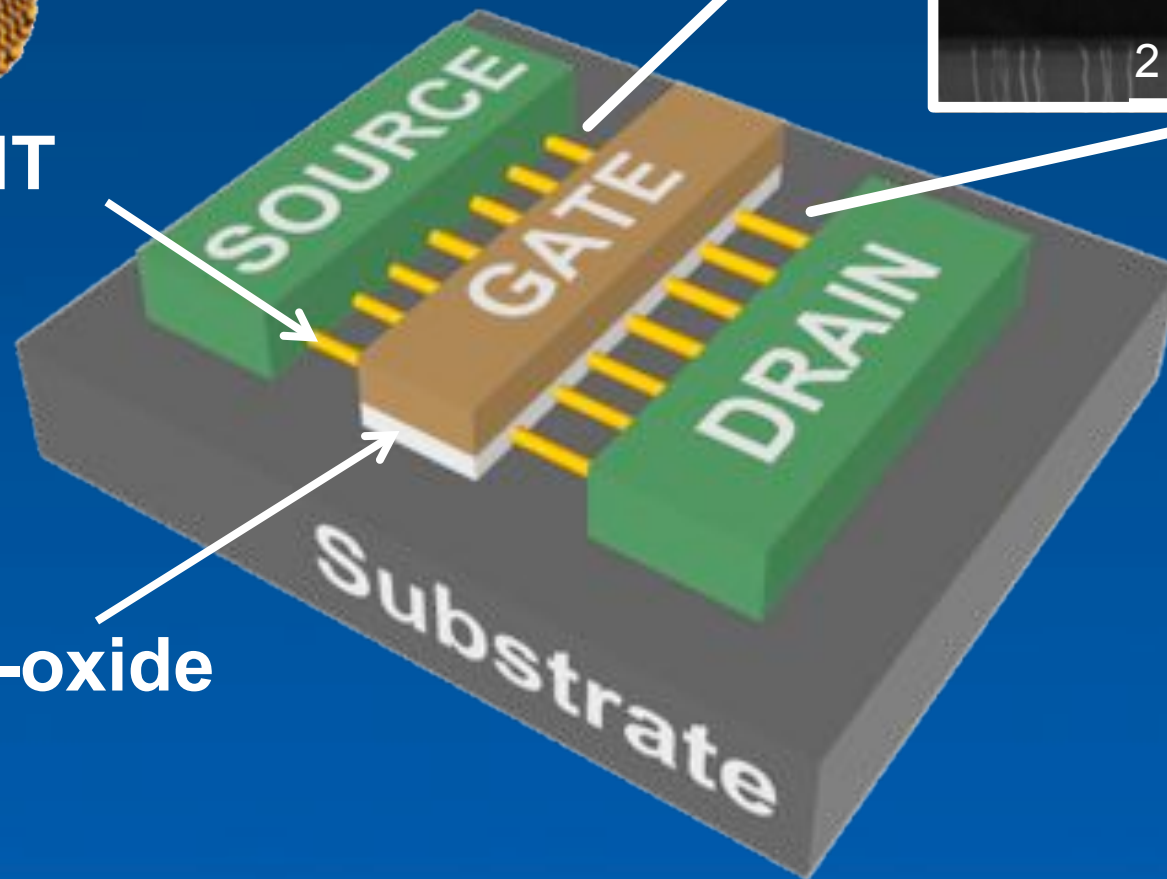
CNT



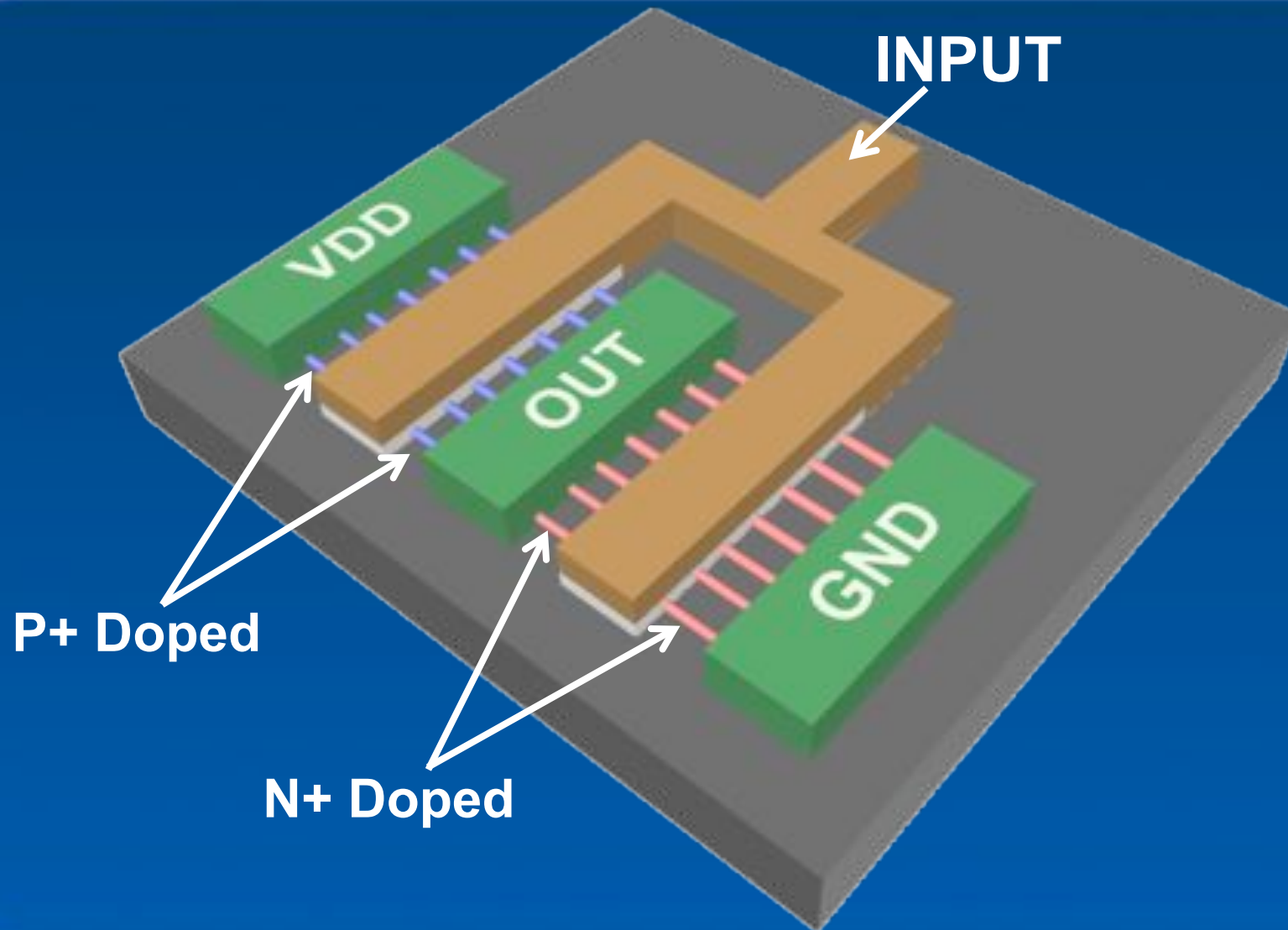
Gate

2 μm

Gate-oxide



Ideal CNFET Inverter




Why CNFETs?

- Best I_{ON}
 - 9nm measurements [Franklin Nano Letters 12]
- 400 mV supply
 - Logic gates [Ding APL 12]
- Major energy-delay-product benefits
 - IBM Power 7 modeled [Chang IEDM 12]

Recent Progress

**First complete sub-system:
Fully digital capacitive sensor interface**



**Single-CNT
ring osc.**



**Flexible
substrate**

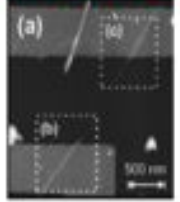


**D-latch,
half adder**

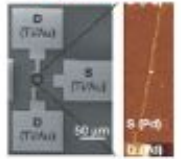


Stand-alone logic elements

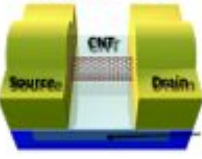
First CNFET



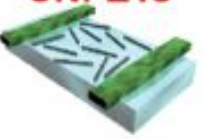
**Ballistic
CNFET**



**Sub-10nm
CNFET**



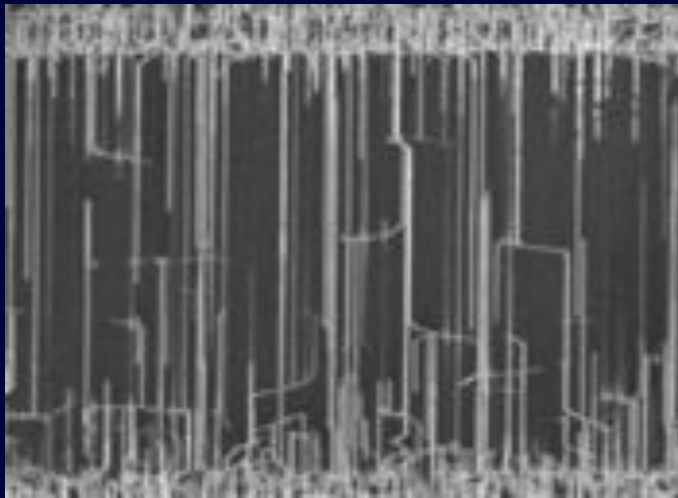
**High
performance
CNFETs**



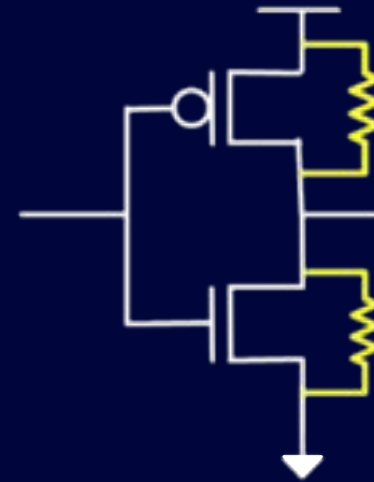
Single devices

BIG Promise, BUT Major Obstacles

Mis-positioned CNTs



Metallic CNTs



Imperfection-immune design essential

First Wafer-Scale Aligned CNT Growth



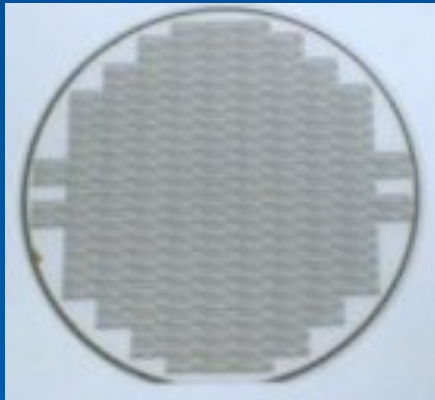
Quartz wafer
with catalyst



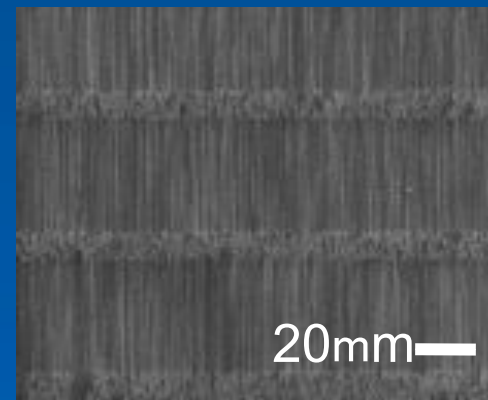
Aligned
CNT growth



Quartz wafer with CNTs



99.5% aligned CNTs

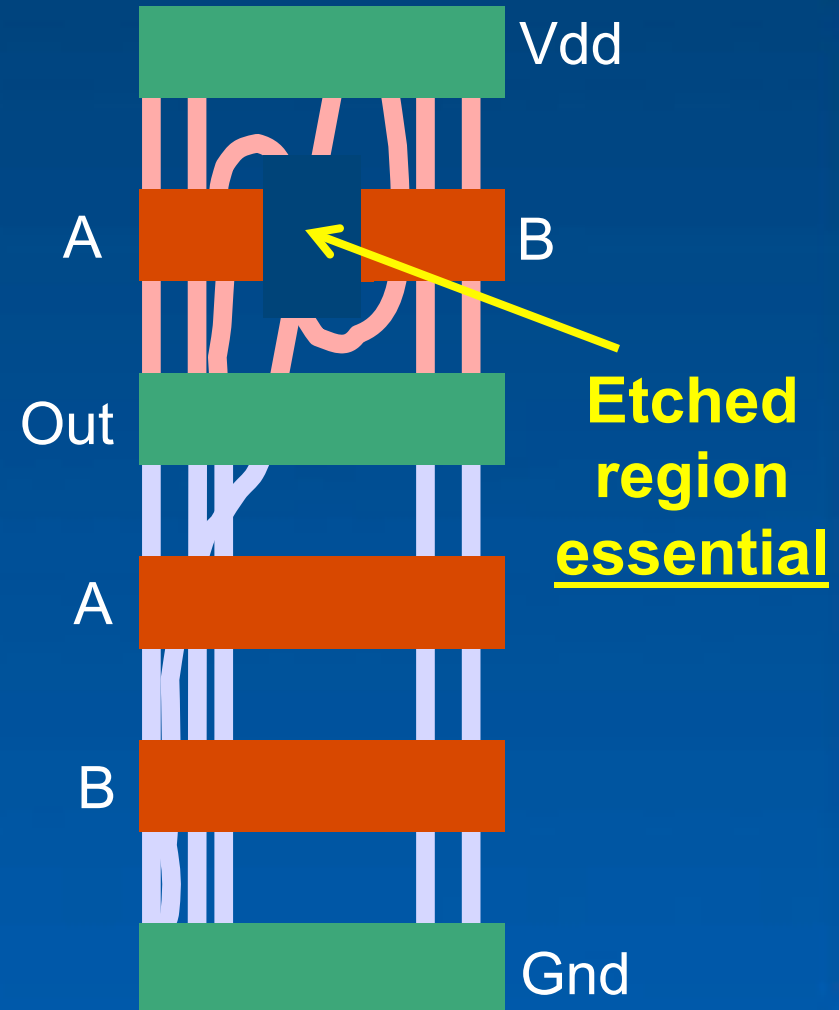


Stanford Nanofabrication Facility

Mis-positioned CNT-Immune NAND

1. Grow CNTs
2. Extended gate, contacts
3. Etch gate & CNTs
4. Dope P & N regions

- Arbitrary logic functions
 - Graph algorithms



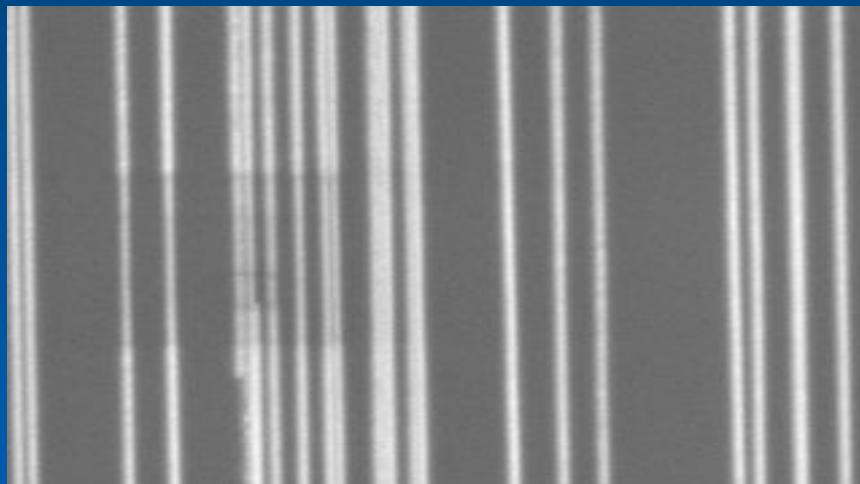
Most Importantly

- VLSI processing
 - No per-unit customization
- VLSI design flow
 - Immune CNT library

m-CNT Removal

- VLSI Metallic CNT Removal
 - Universally effective
 - All logic designs
 - VLSI processing & design flows

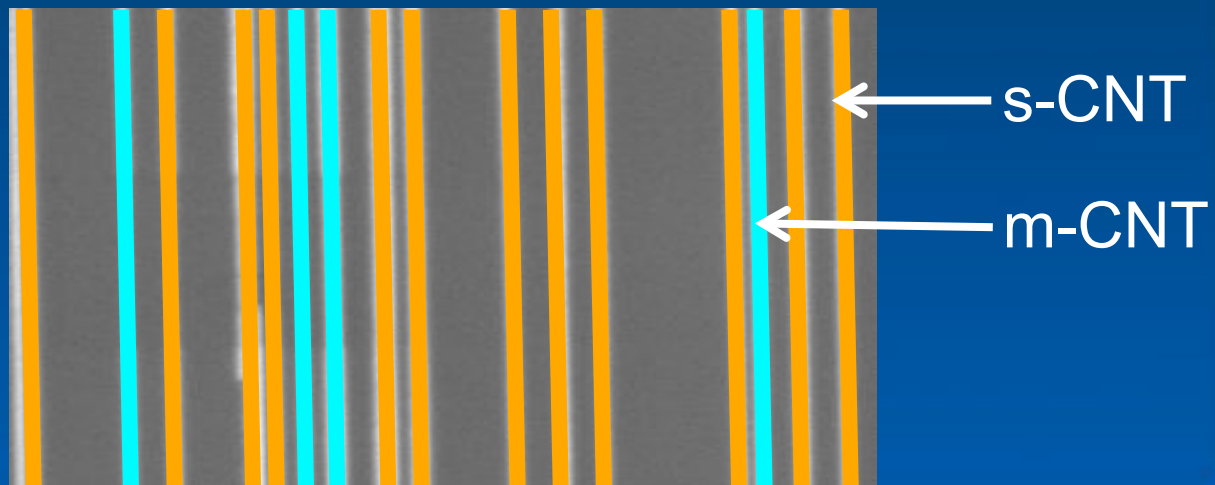
Chip-Scale Electrical Breakdown



m-CNT Removal

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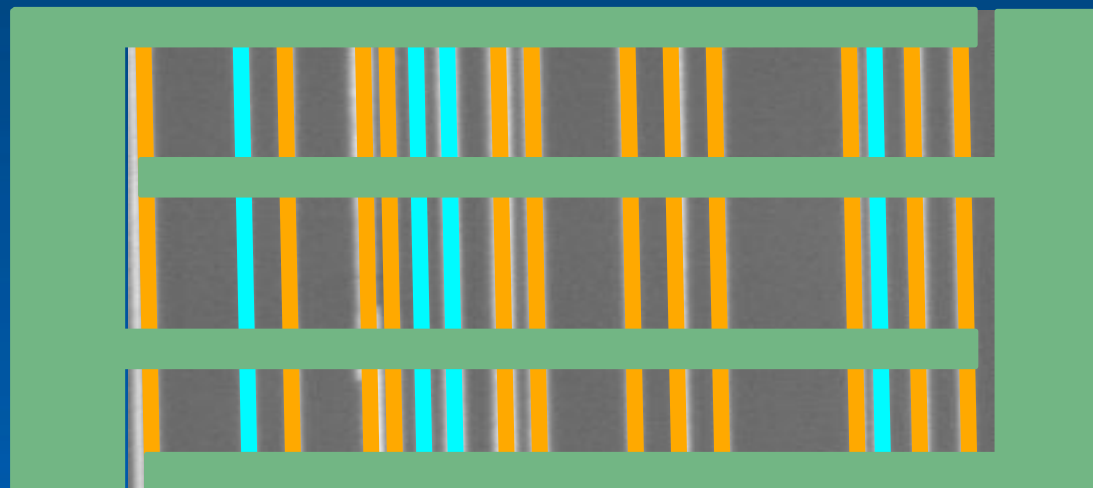
Chip-Scale Electrical Breakdown



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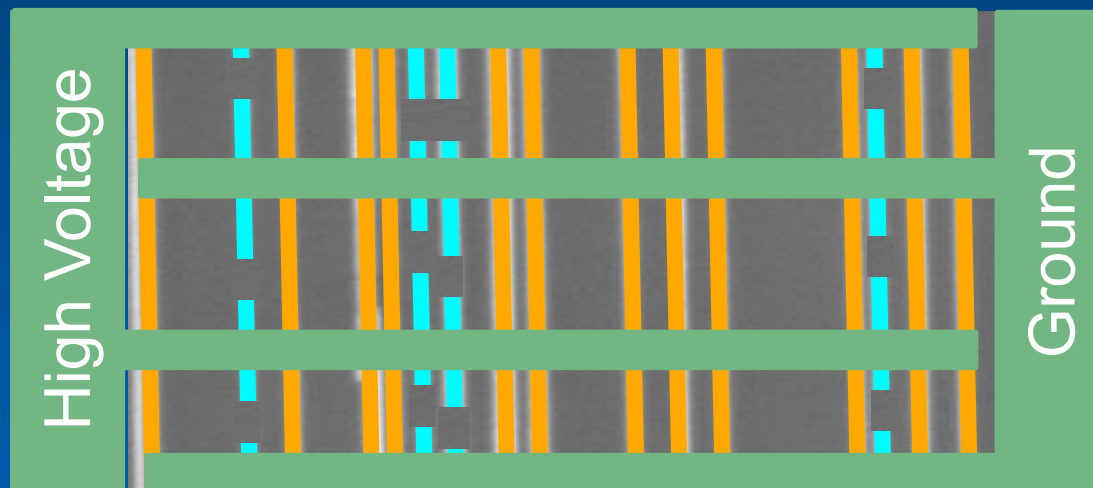
Fabricate VMR electrodes



m-CNT Removal

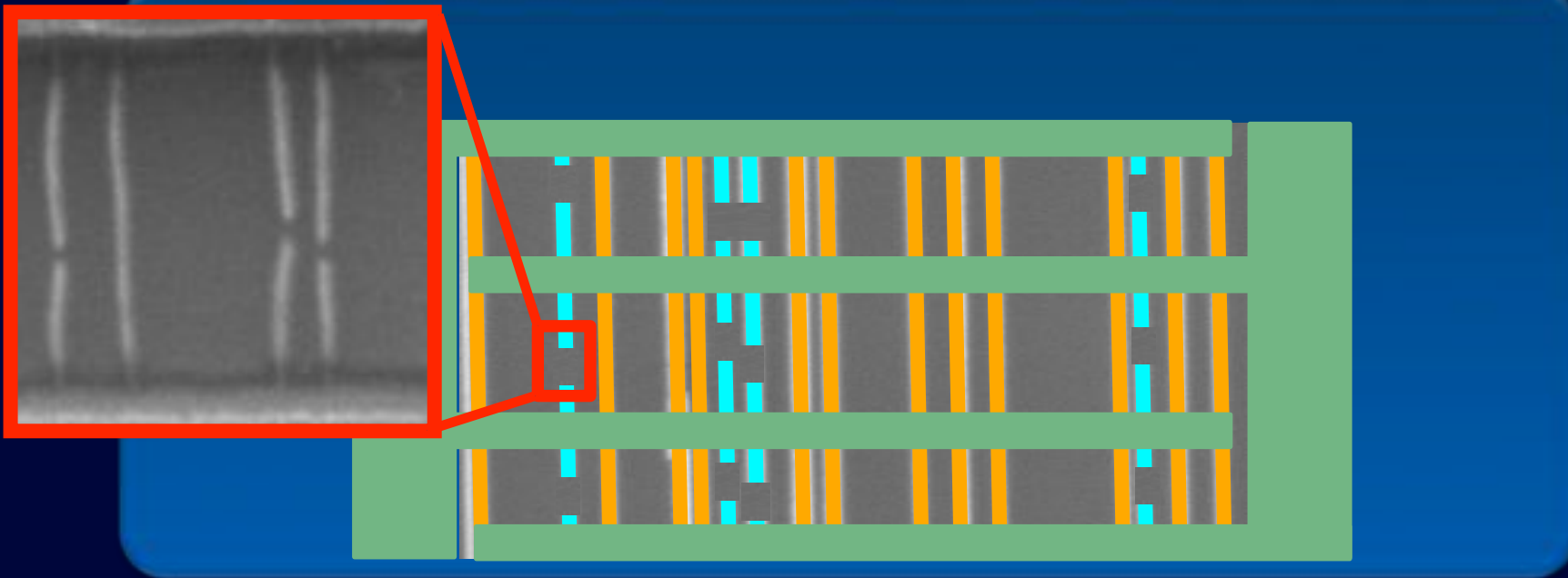
- VLSI Metallic CNT Removal
 - Universally effective
 - All logic designs
 - VLSI processing & design flows

Electrical Breakdown (back-gate)



m-CNT Removal

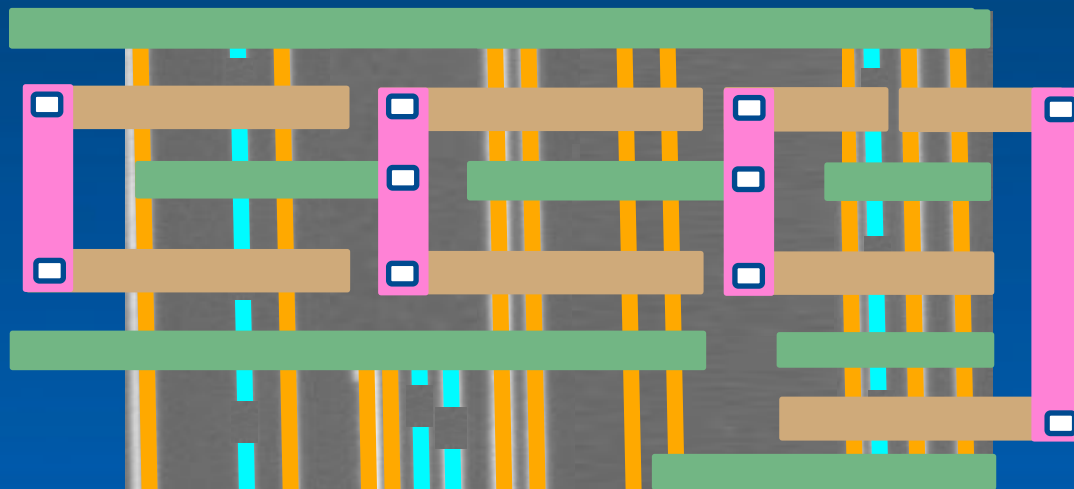
- VLSI Metallic CNT Removal
 - Universally effective
 - All logic designs
 - VLSI processing & design flows



m-CNT Removal

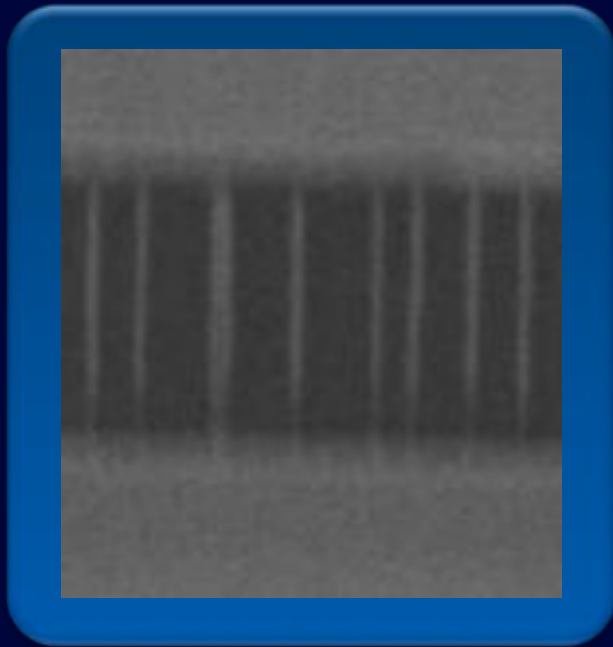
- VLSI Metallic CNT Removal
 - Universally effective
 - All logic designs
 - VLSI processing & design flows

Top-gates (mis-positioned CNT-immune layout), wires



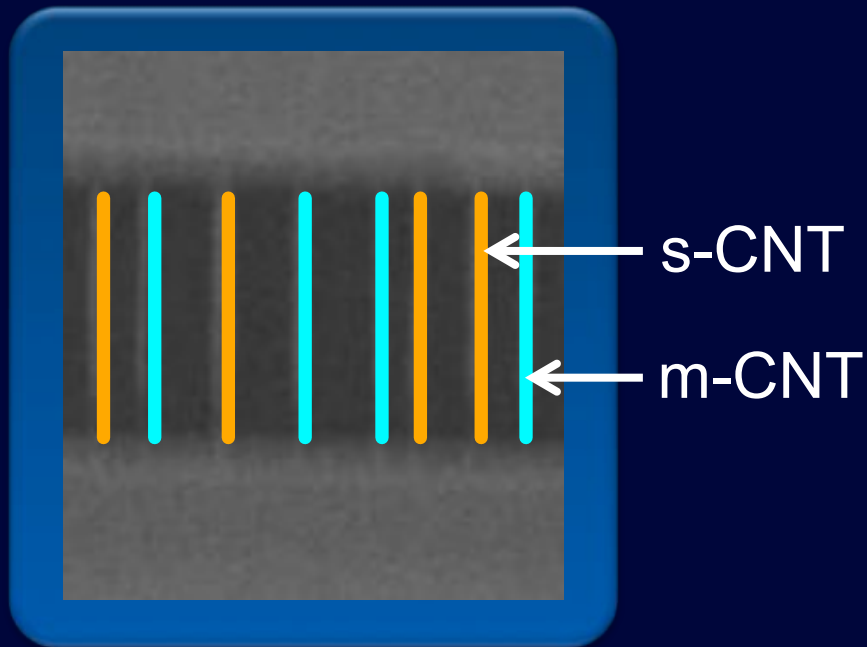
VMR Performance

m-CNT vs. s-CNT selectivity



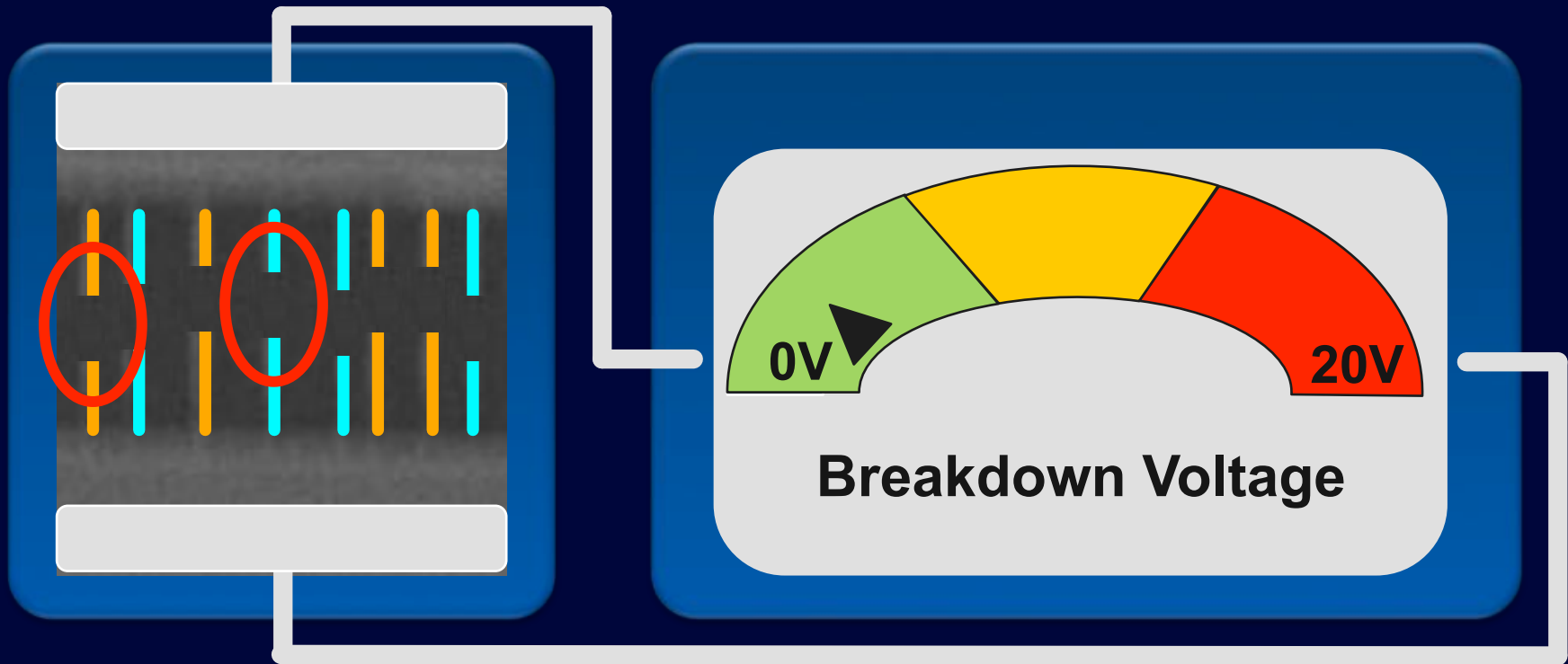
VMR Performance

m-CNT vs. s-CNT selectivity



VMR Performance

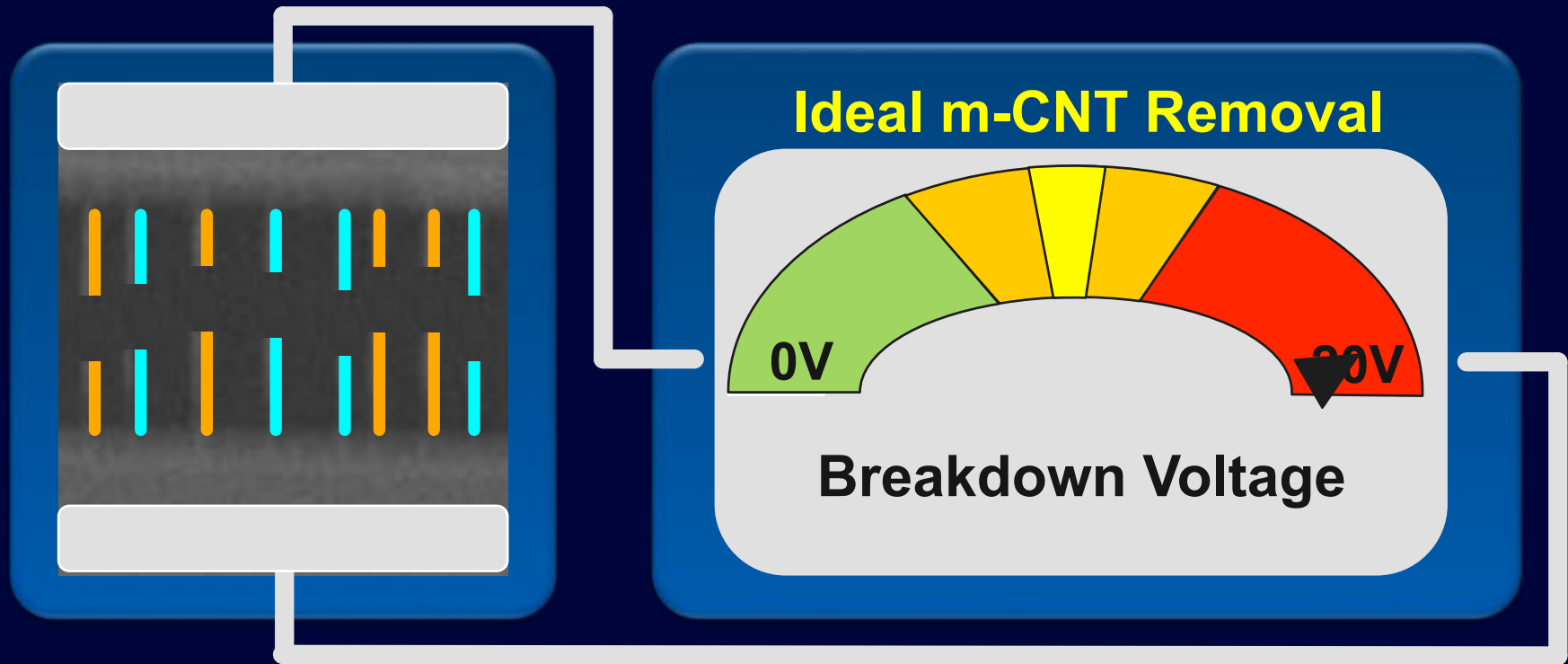
m-CNT vs. s-CNT selectivity



Exceeding Breakdown Voltage!

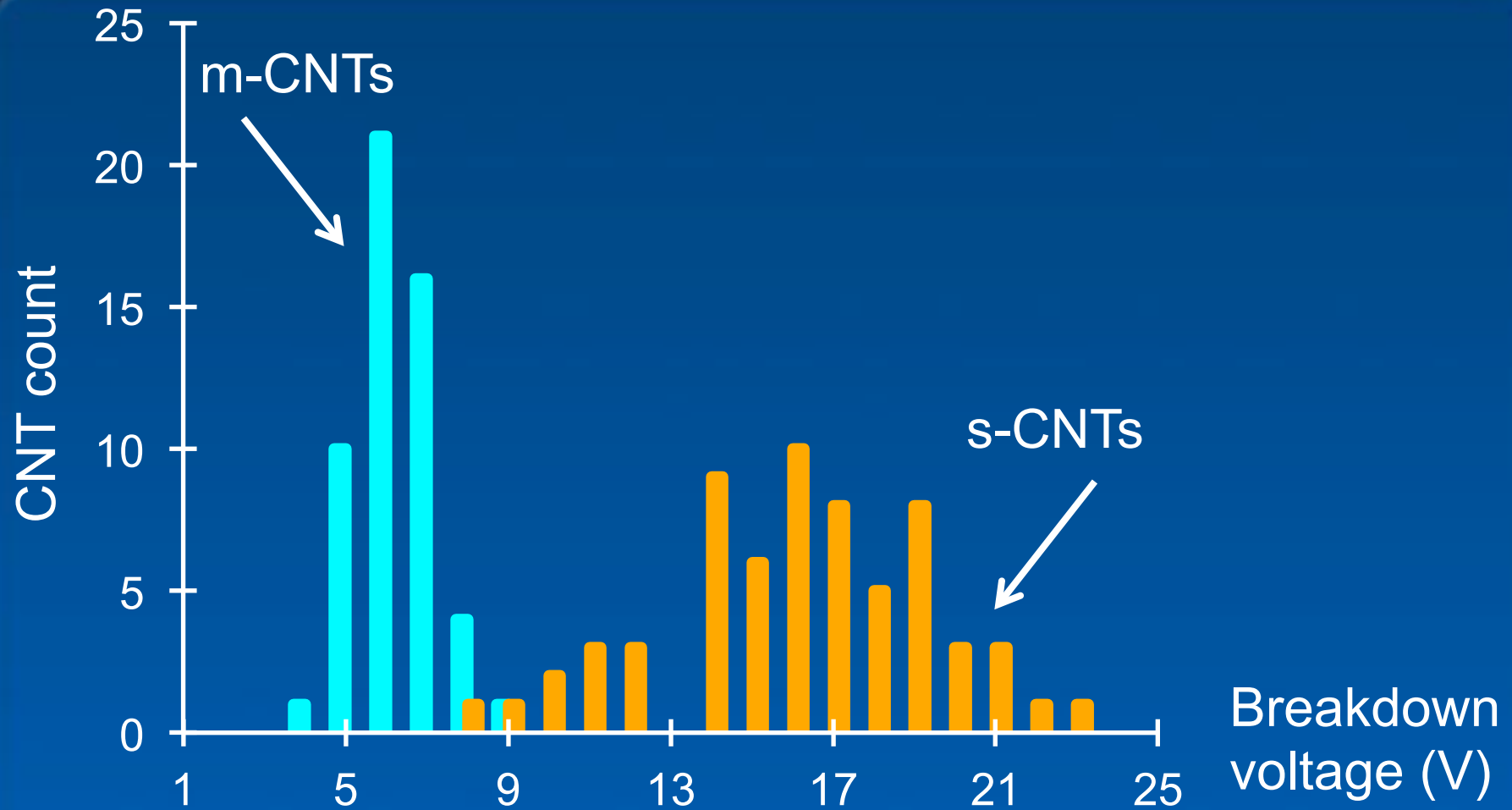
VMR Performance

m-CNT vs. s-CNT selectivity



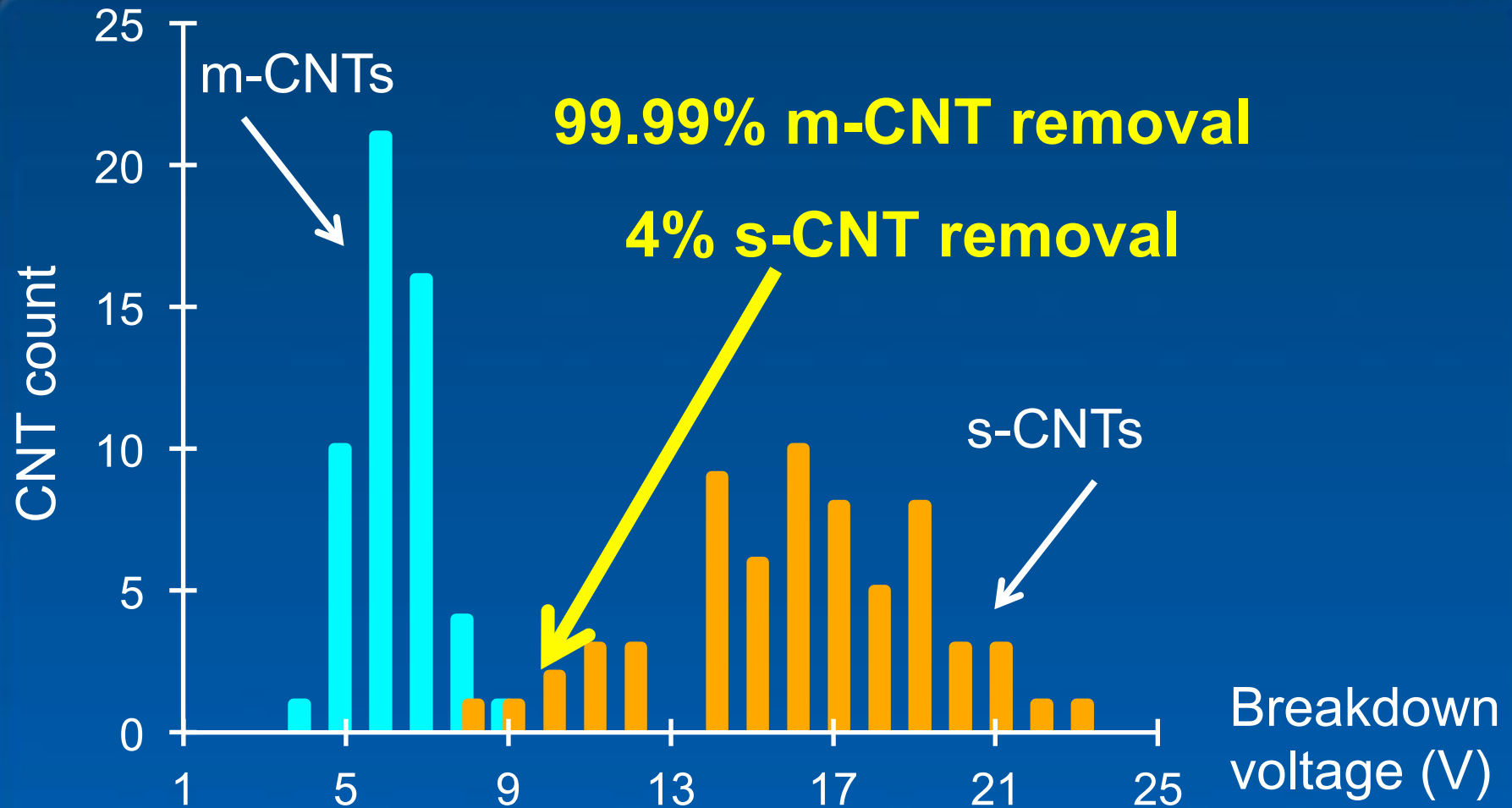
VMR Performance

Experimental Distribution



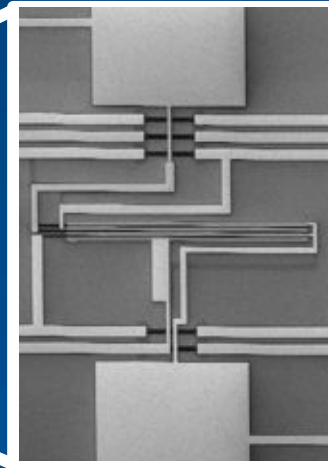
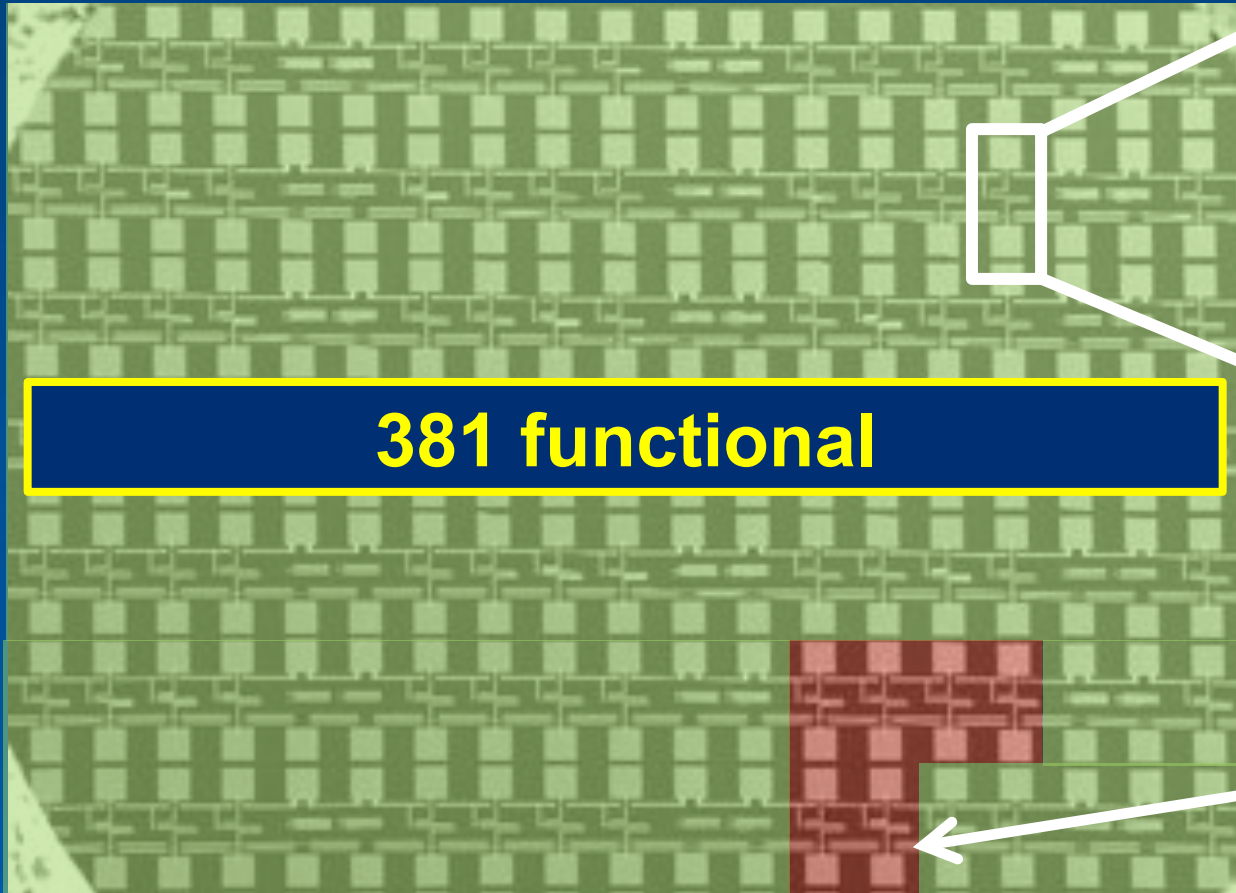
VMR Performance

Experimental Distribution



Circuit Robustness

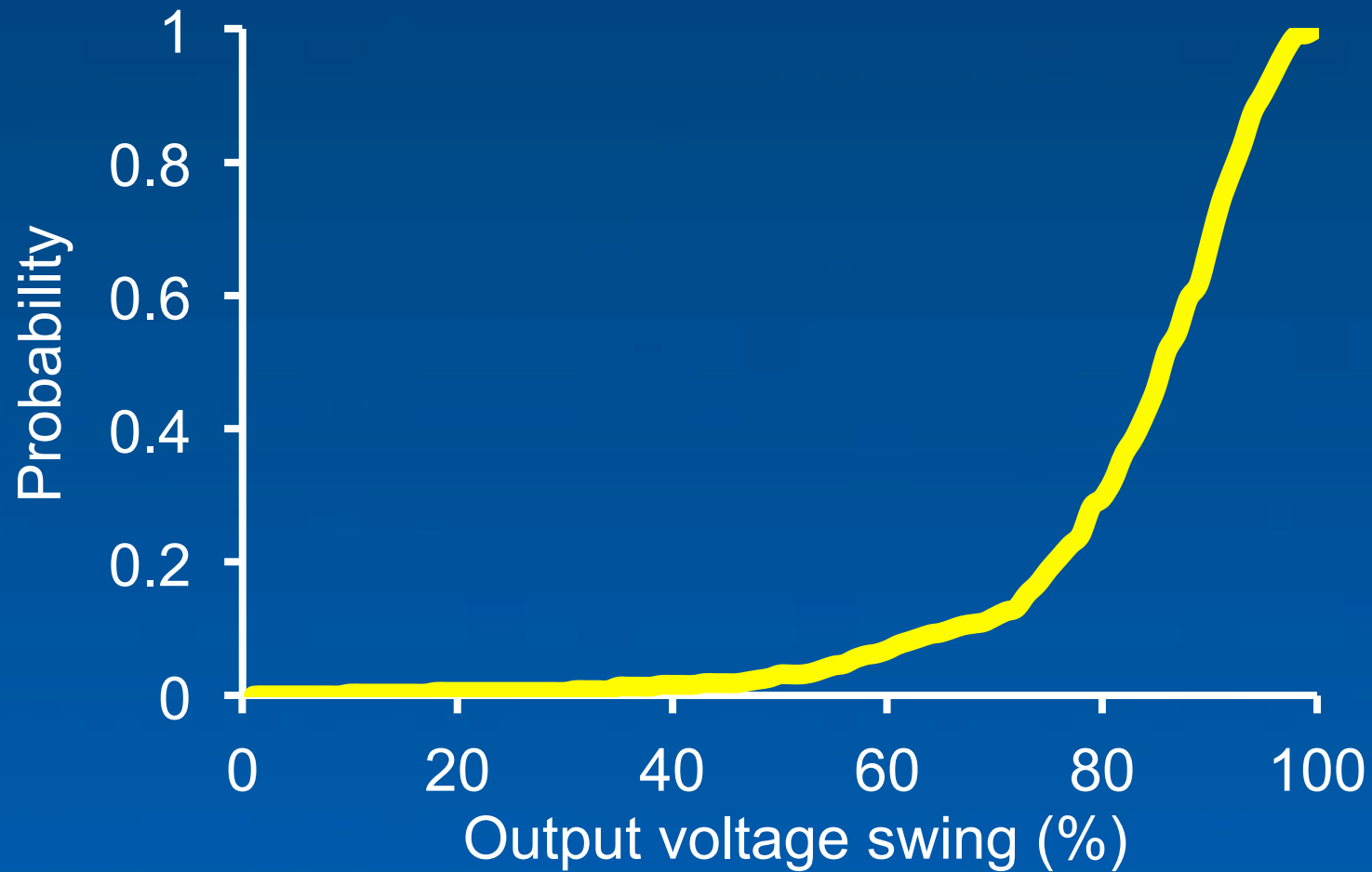
400 inverters



19
clustered fails
(non-CNT issues)

Circuit Robustness

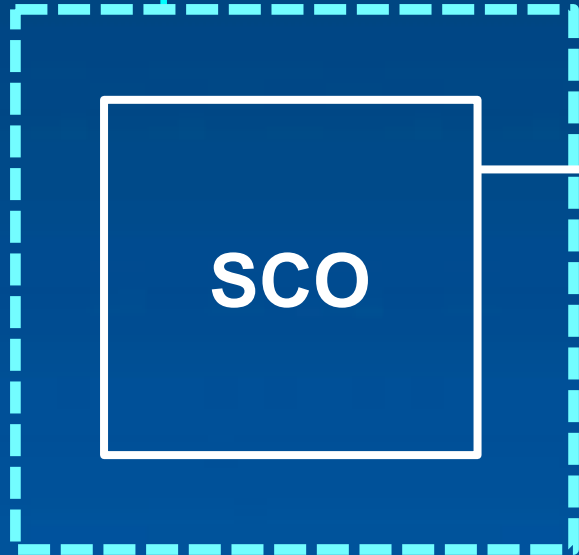
Inverter output swing: cumulative distribution



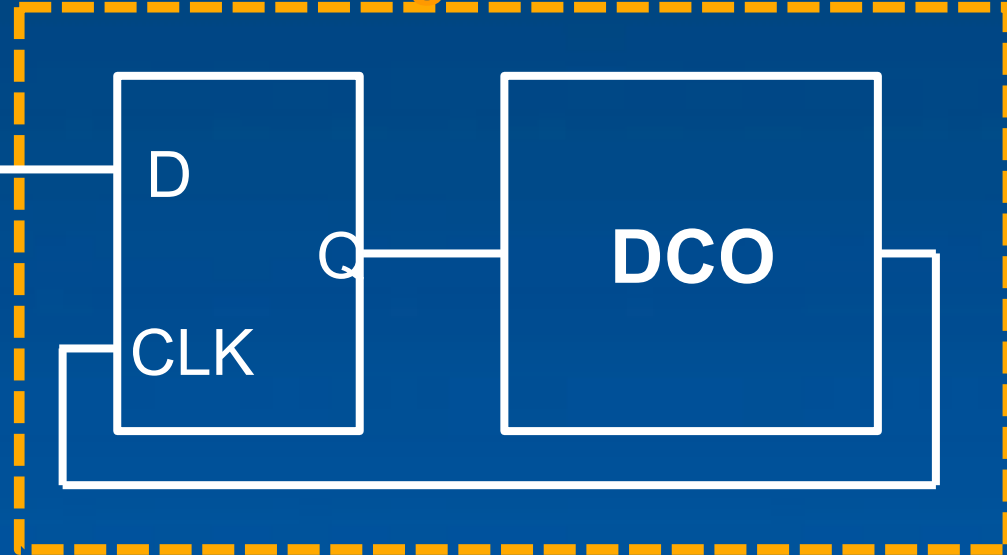
Complete Sub-System

Complete Capacitive Sensor Interface

Freq. Modulation



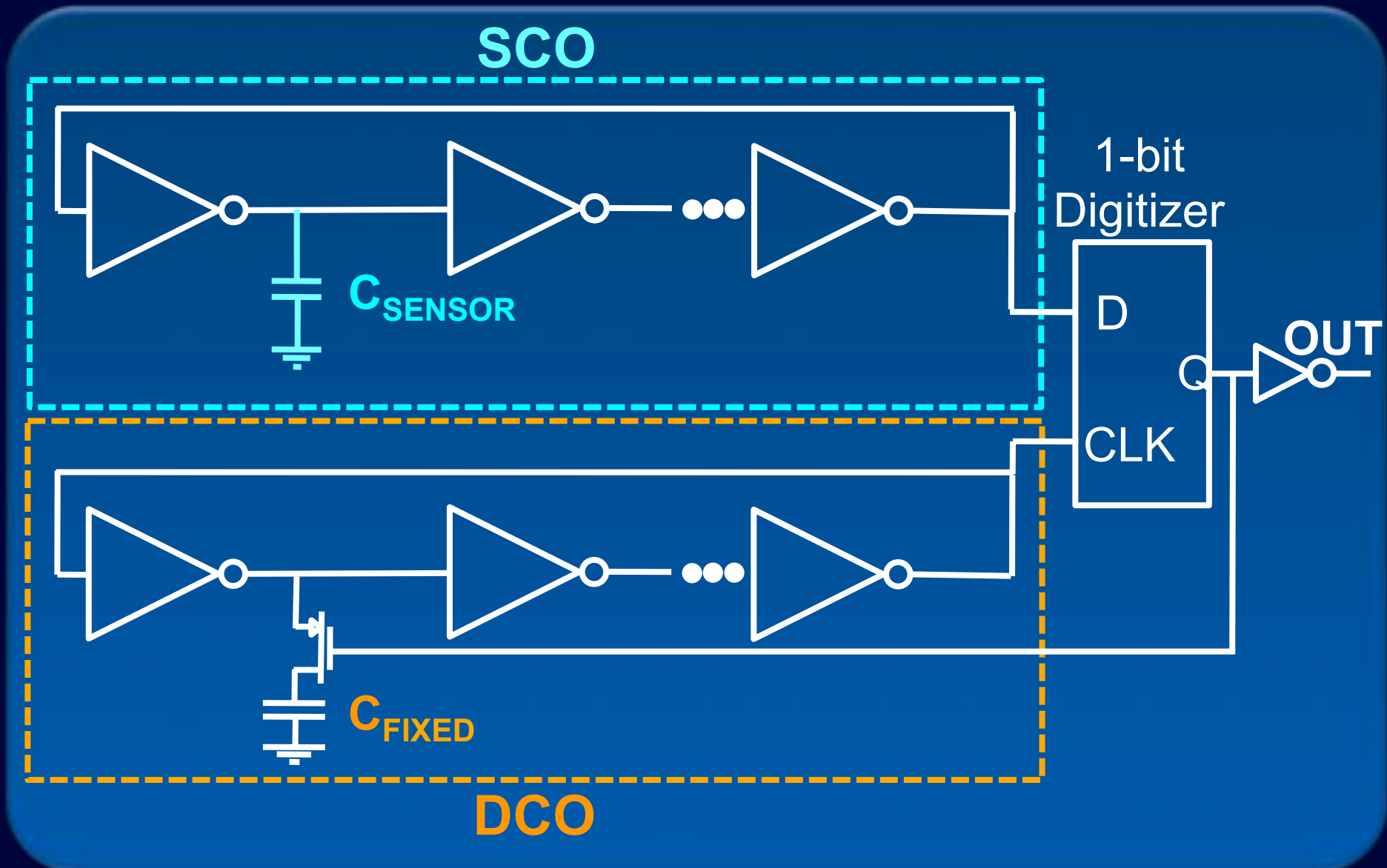
Digital PLL



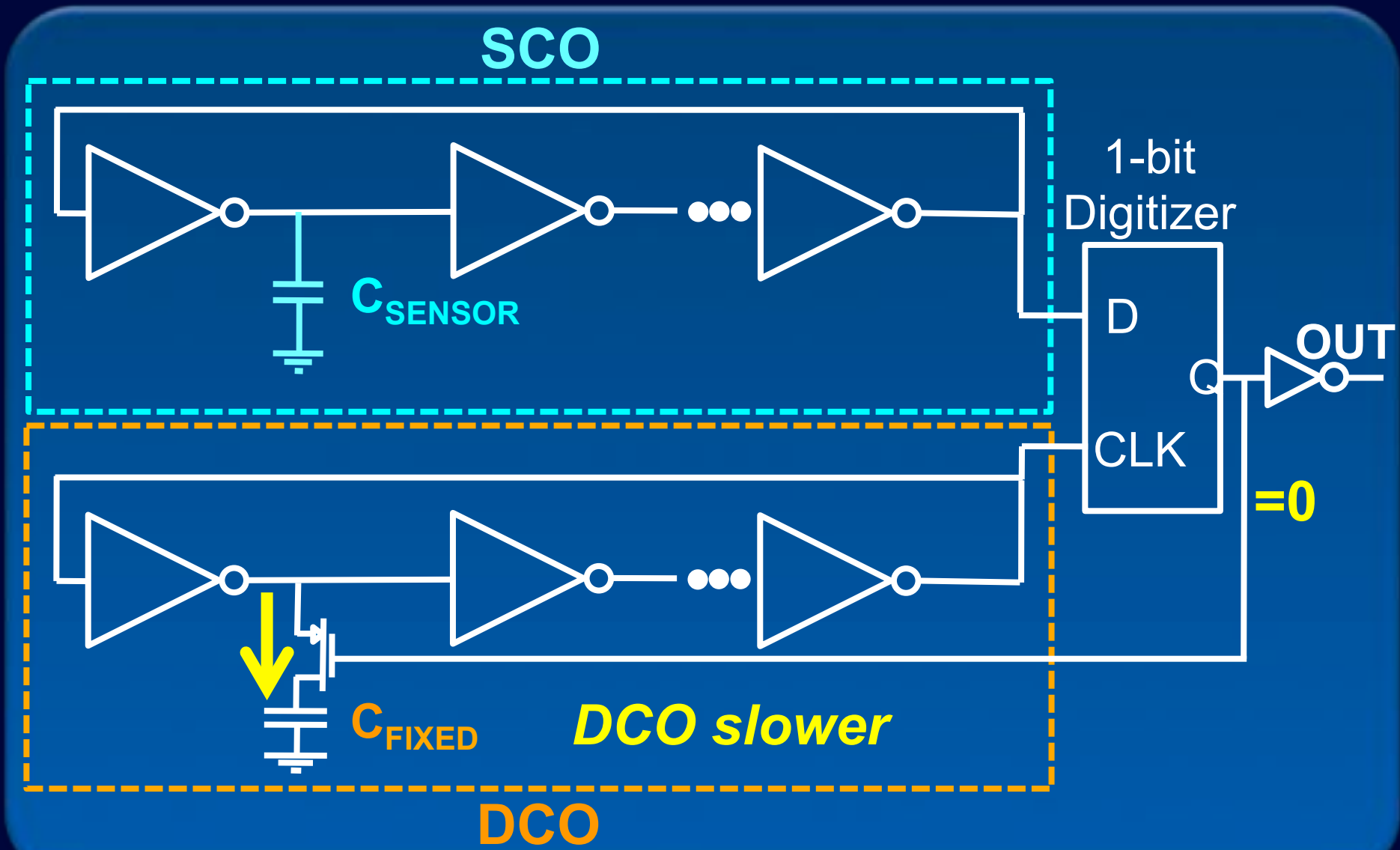
SCO = Sensor-controlled oscillator

DCO = Digitally-controlled oscillator

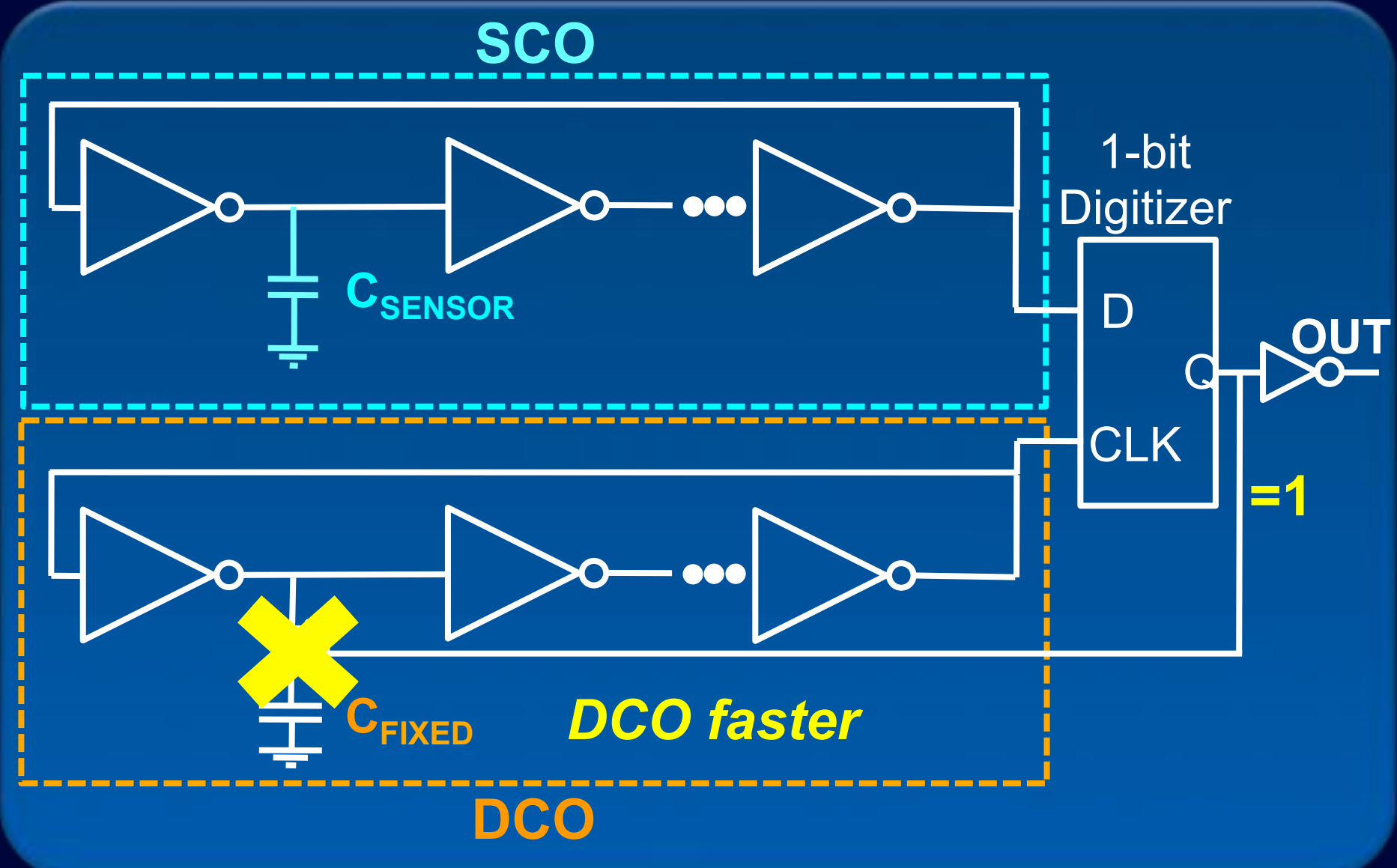
Capacitive Sensor Interface



Circuit Operation

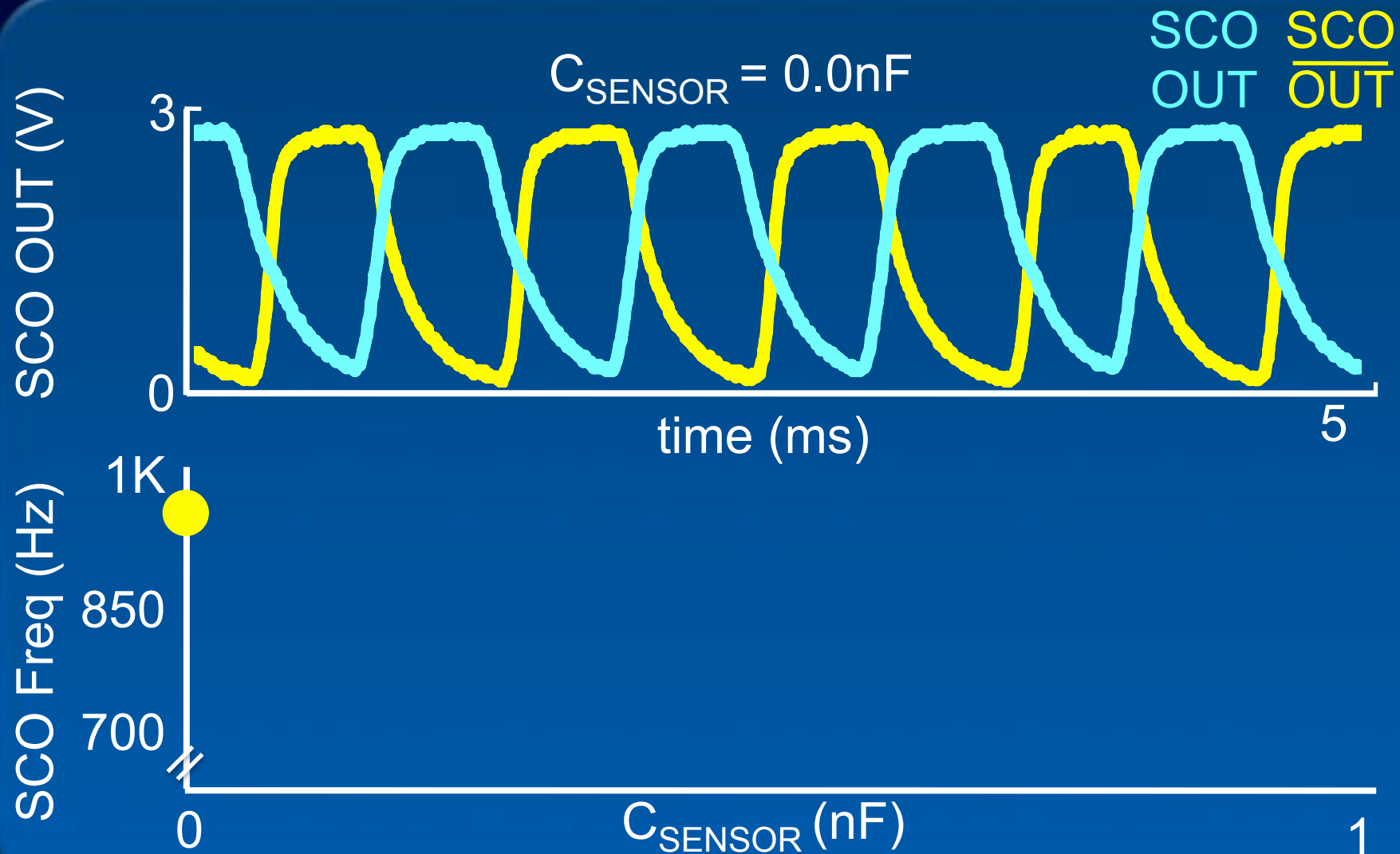


Circuit Operation



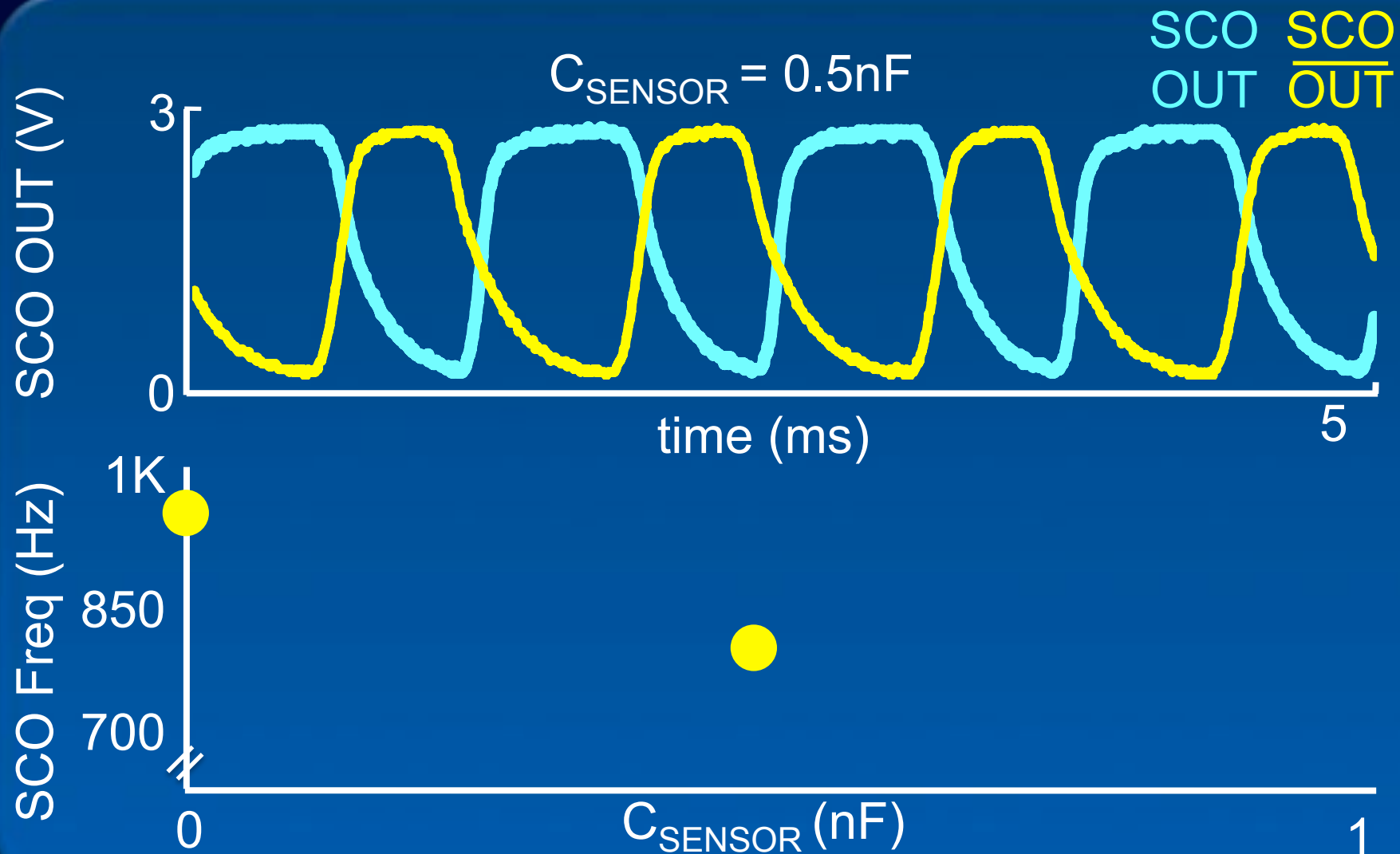
Ring Oscillator Performance

SCO vs. C_{SENSOR}



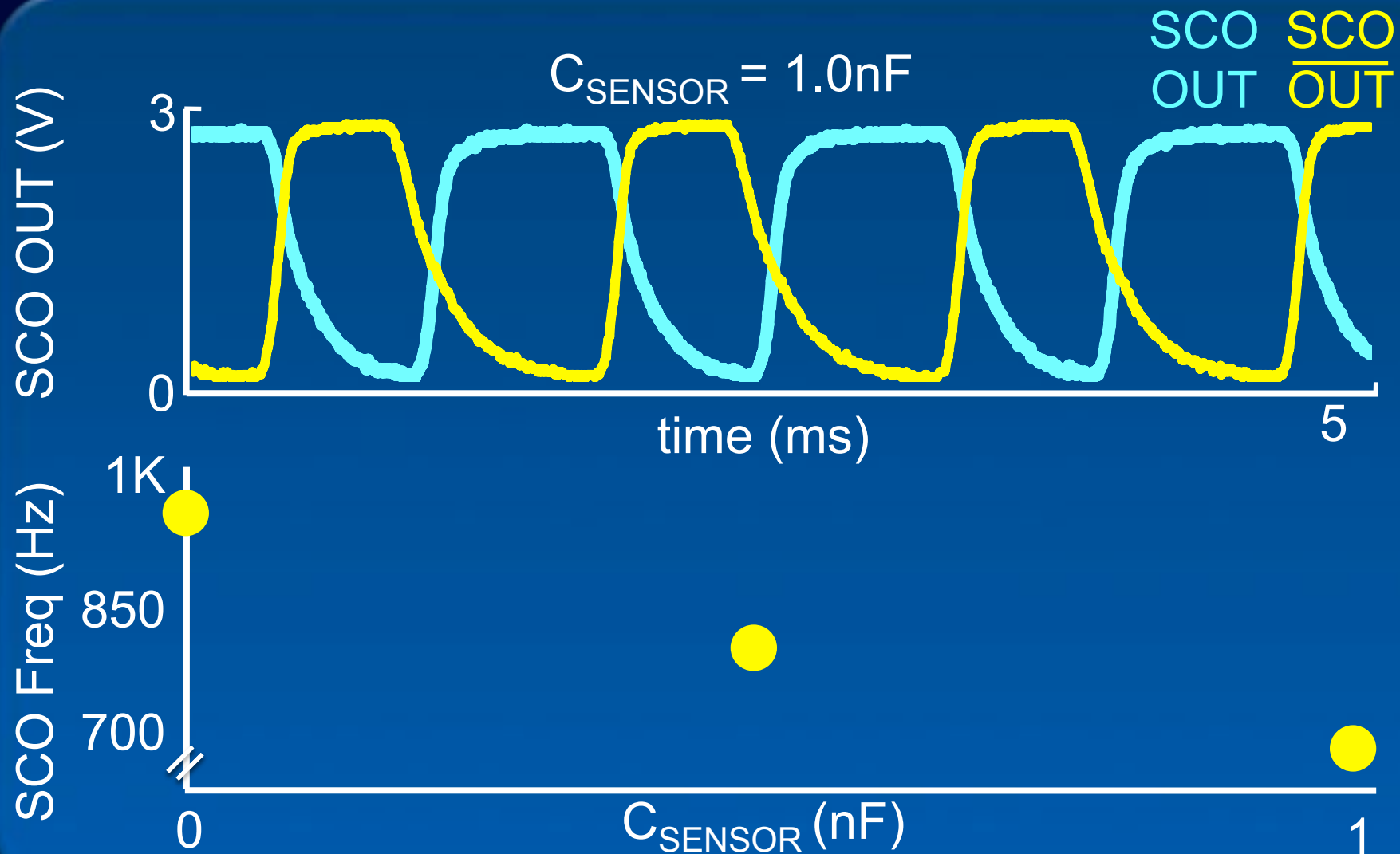
Ring Oscillator Performance

SCO vs. C_{SENSOR}



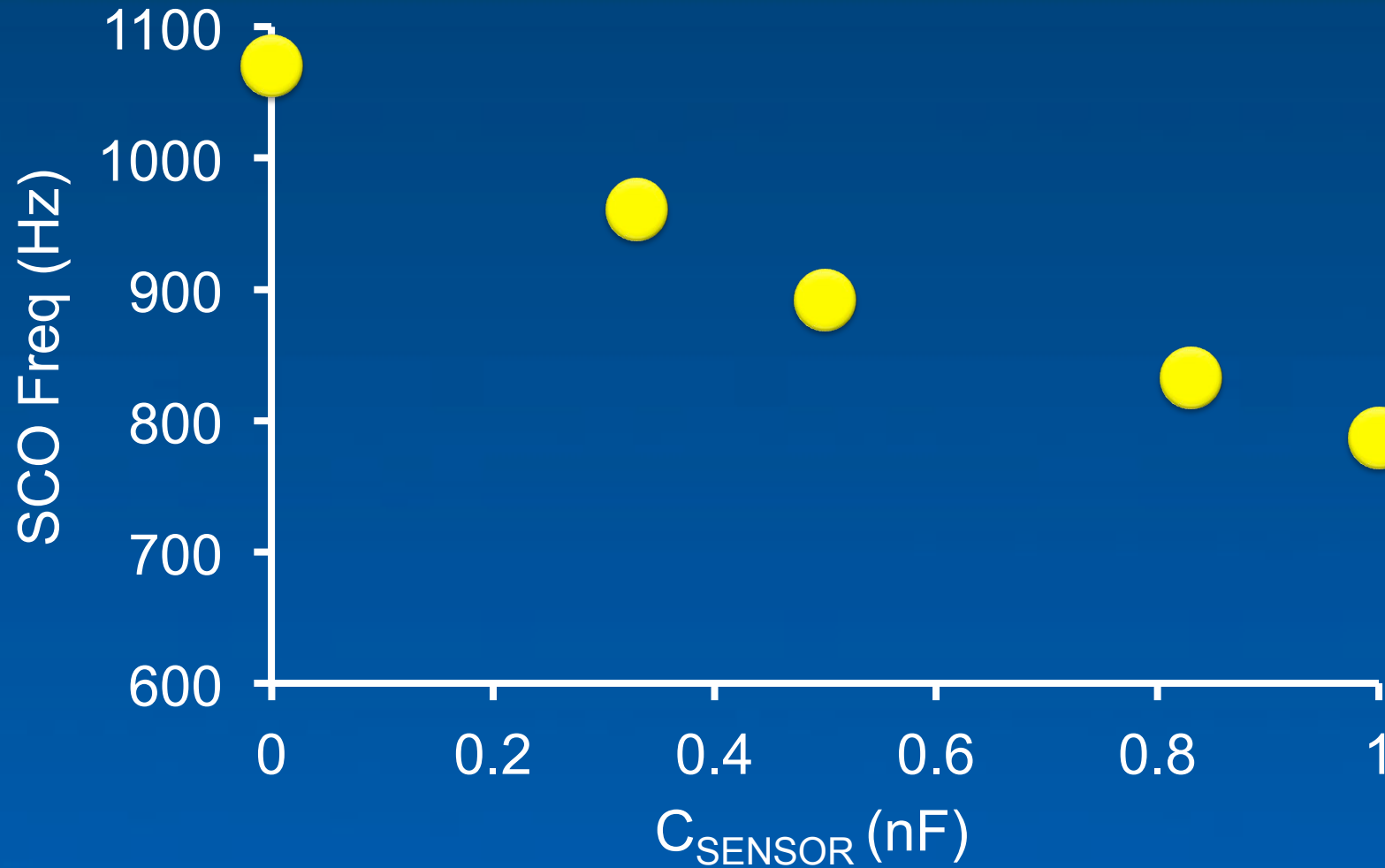
Ring Oscillator Performance

SCO vs. C_{SENSOR}



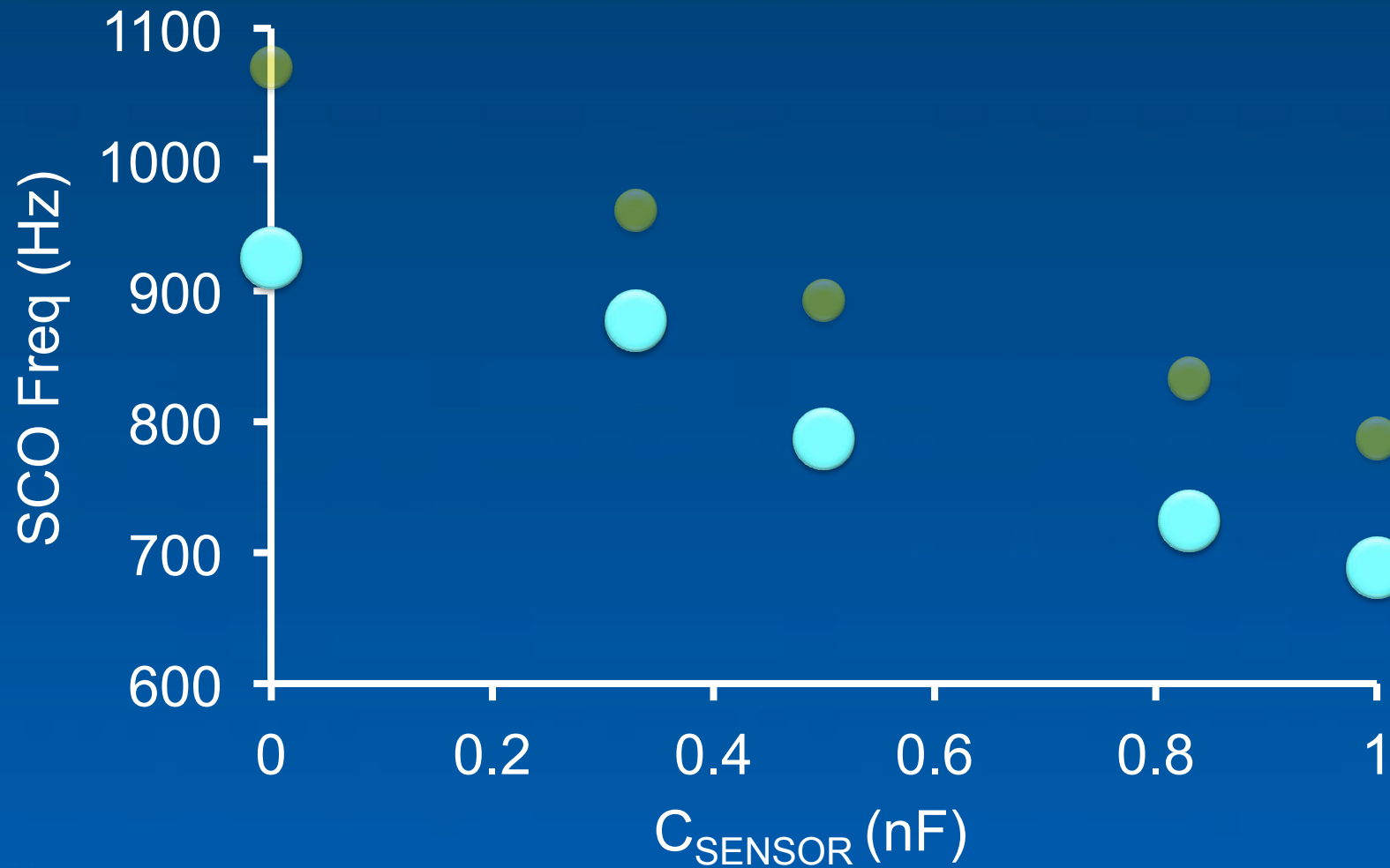
Ring Oscillator Performance

Multiple SCOs



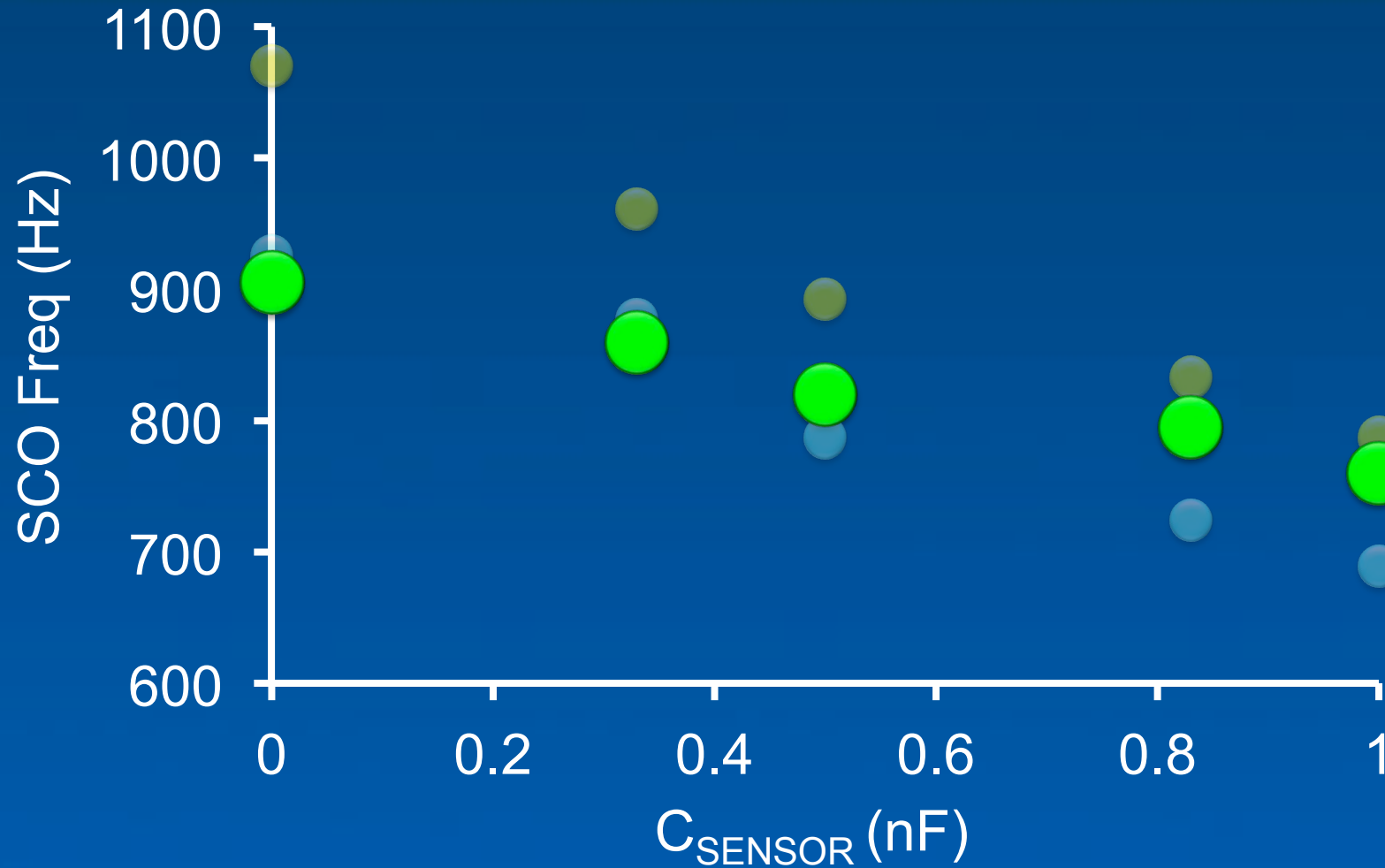
Ring Oscillator Performance

Multiple SCOs



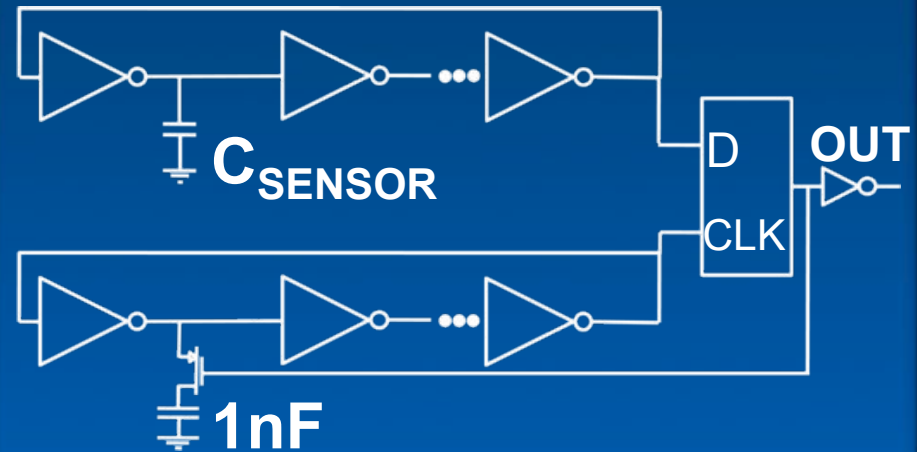
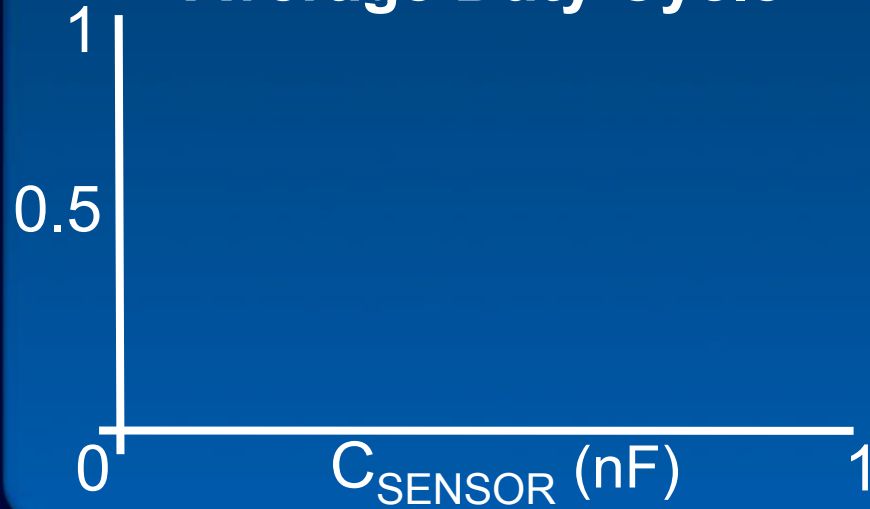
Ring Oscillator Performance

Multiple SCOs



Ring Oscillator Performance

Average Duty Cycle

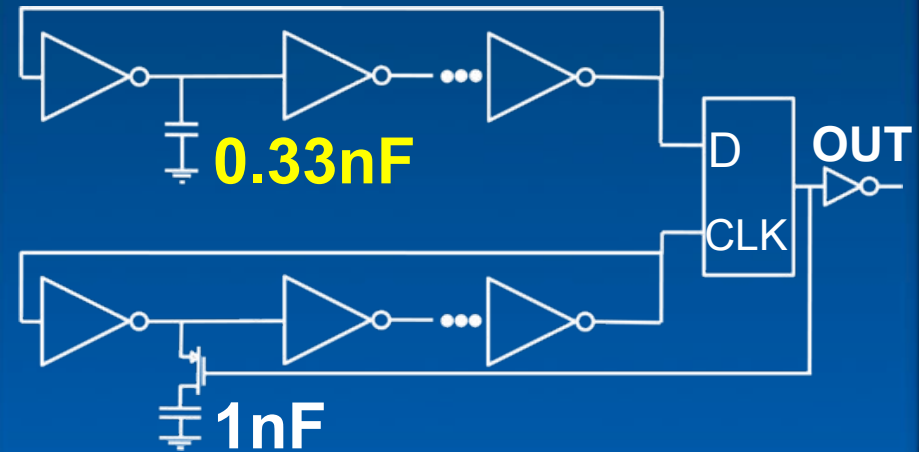
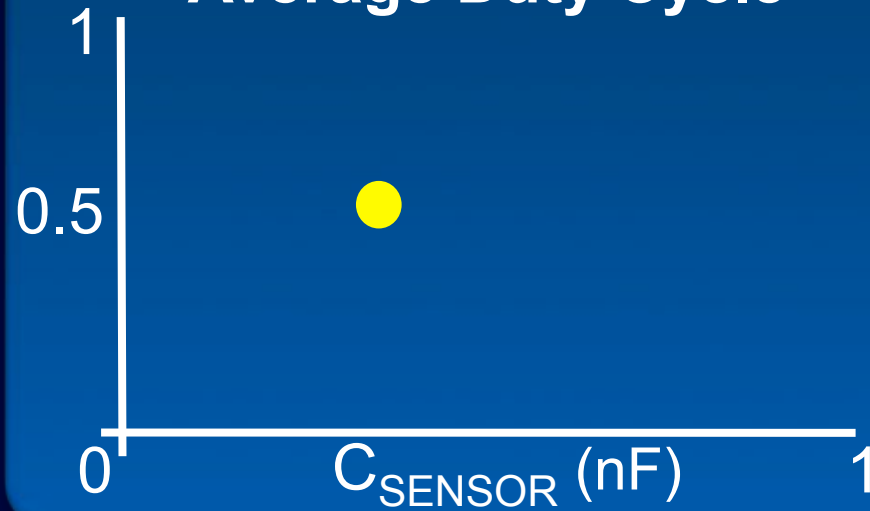


Sampled Output (OUT)

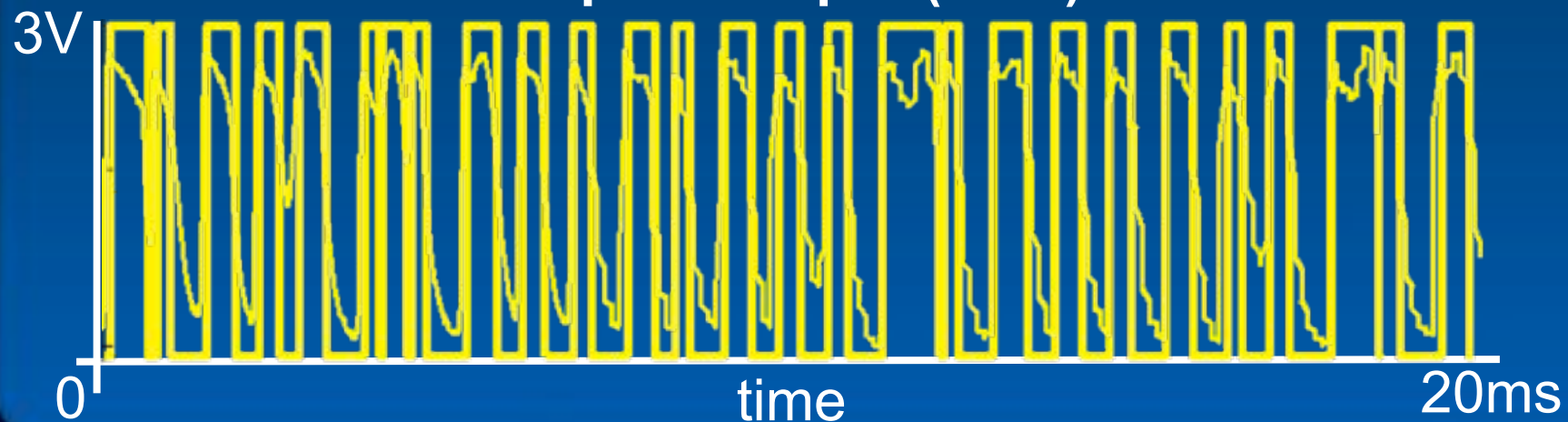


Ring Oscillator Performance

Average Duty Cycle

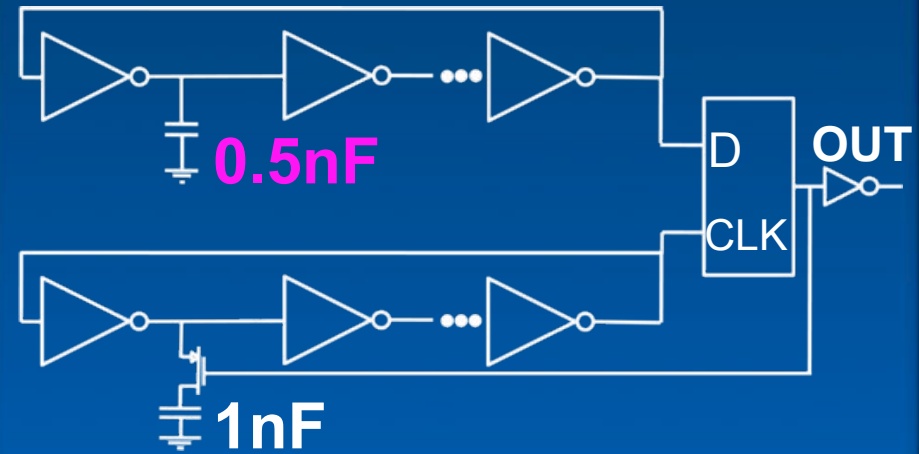
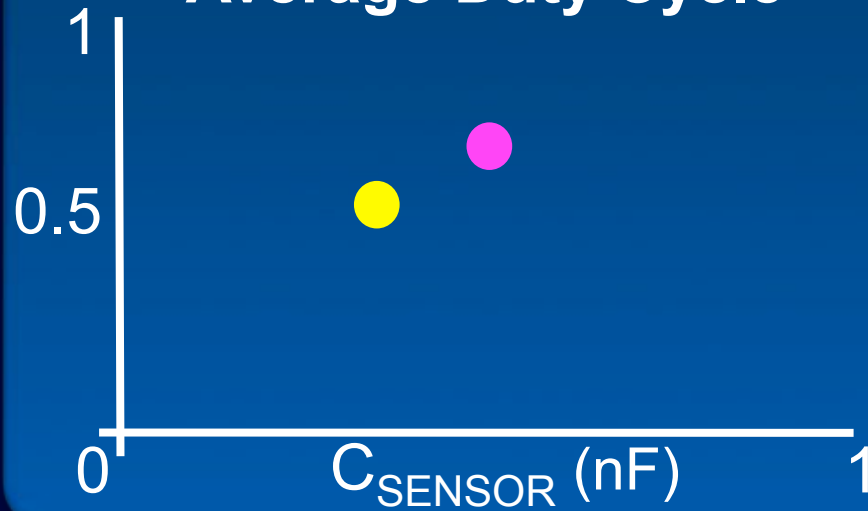


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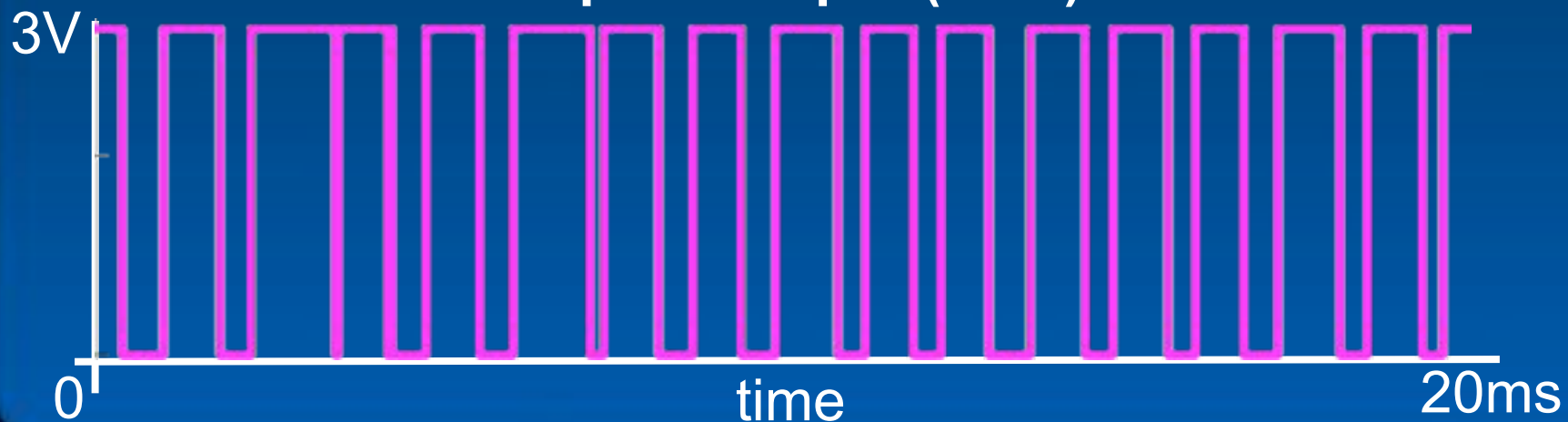


Ring Oscillator Performance

Average Duty Cycle

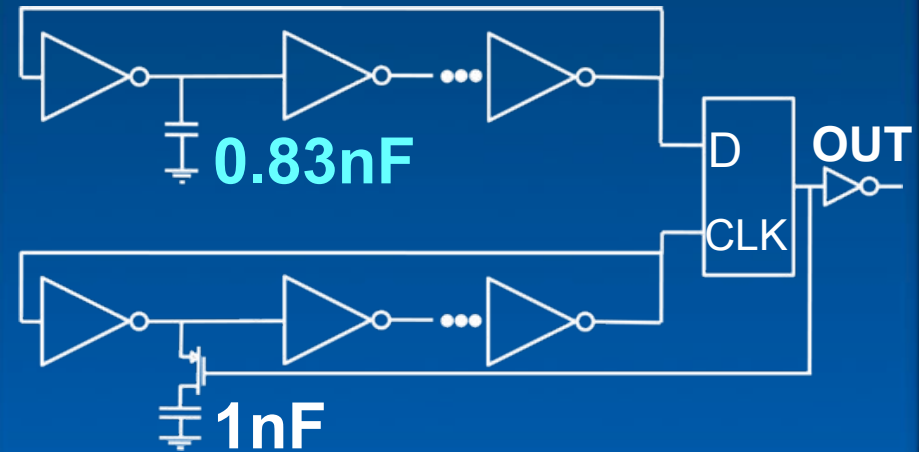
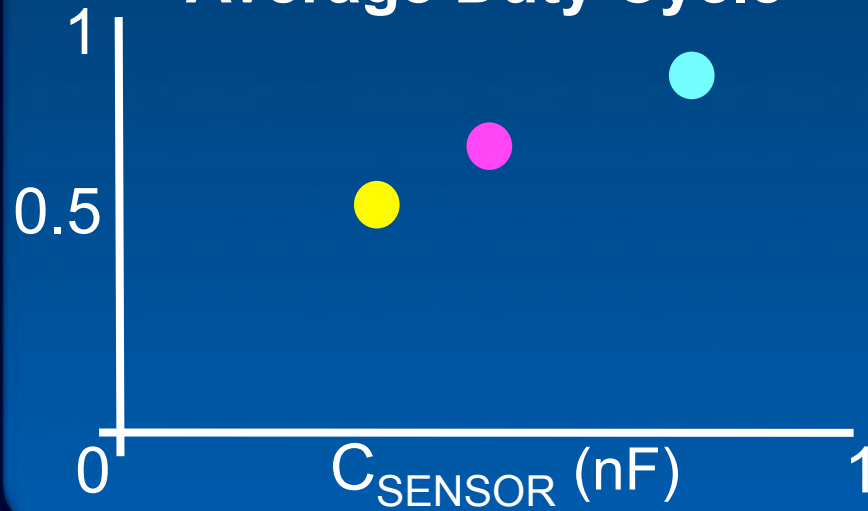


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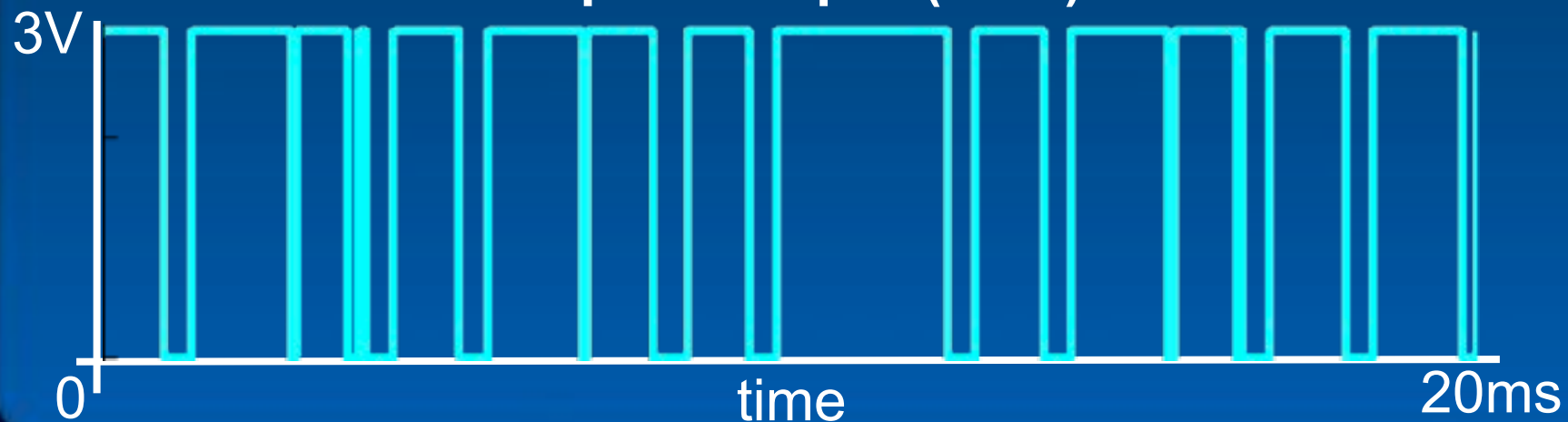


Ring Oscillator Performance

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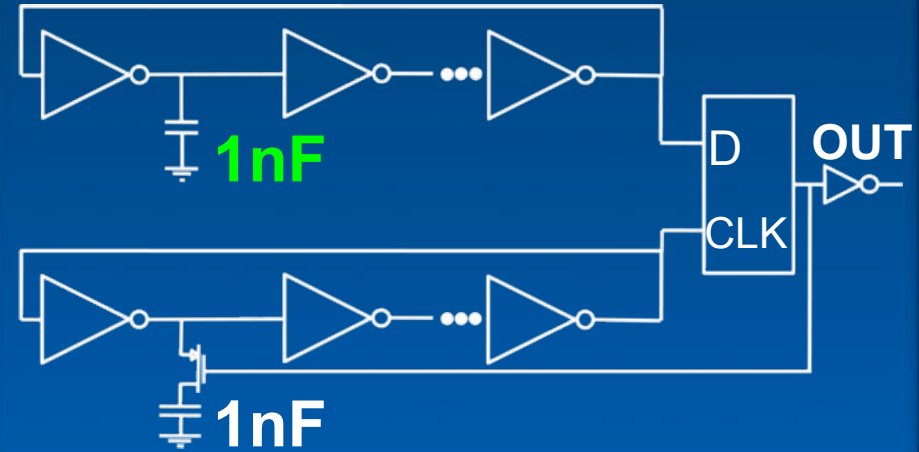
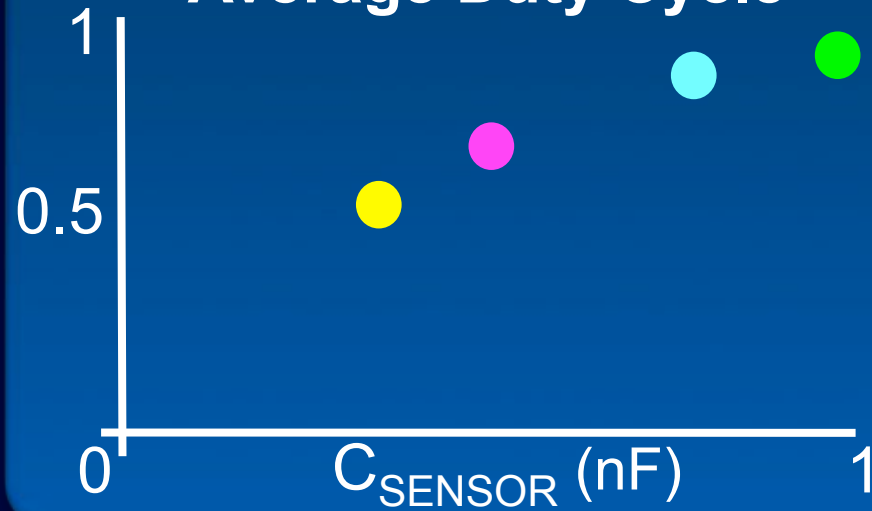


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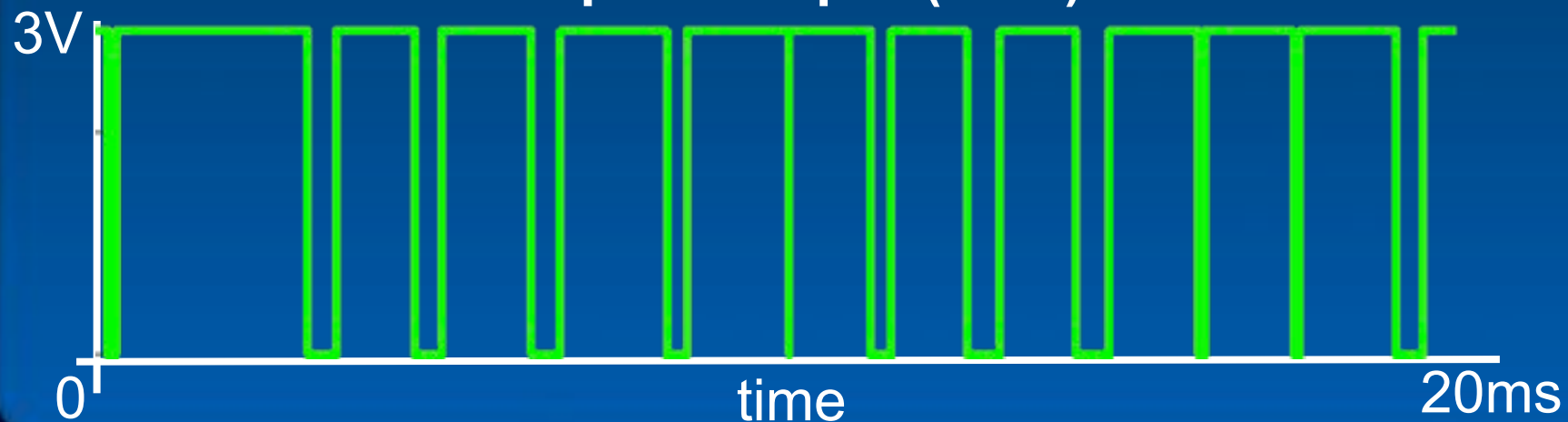


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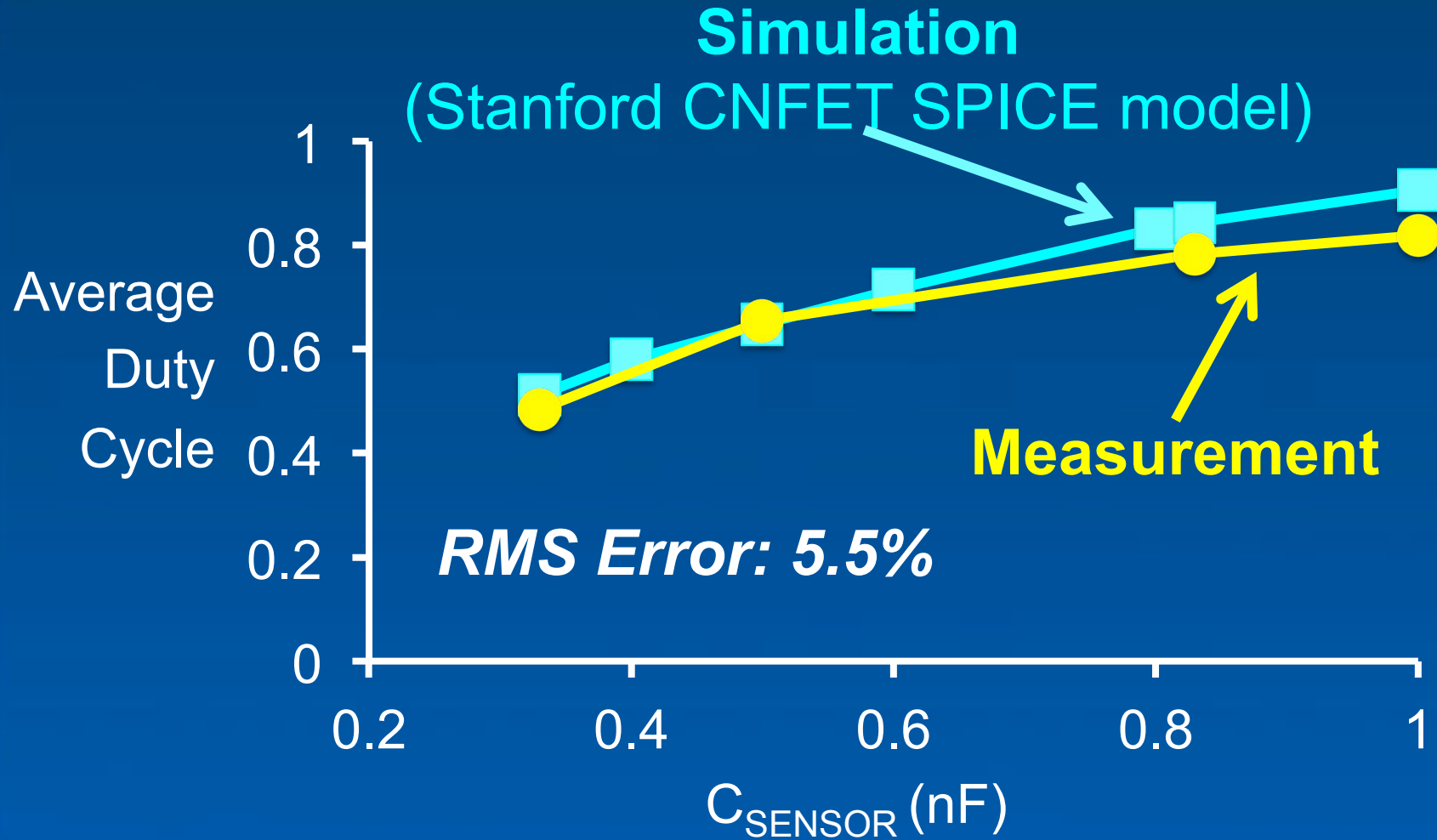
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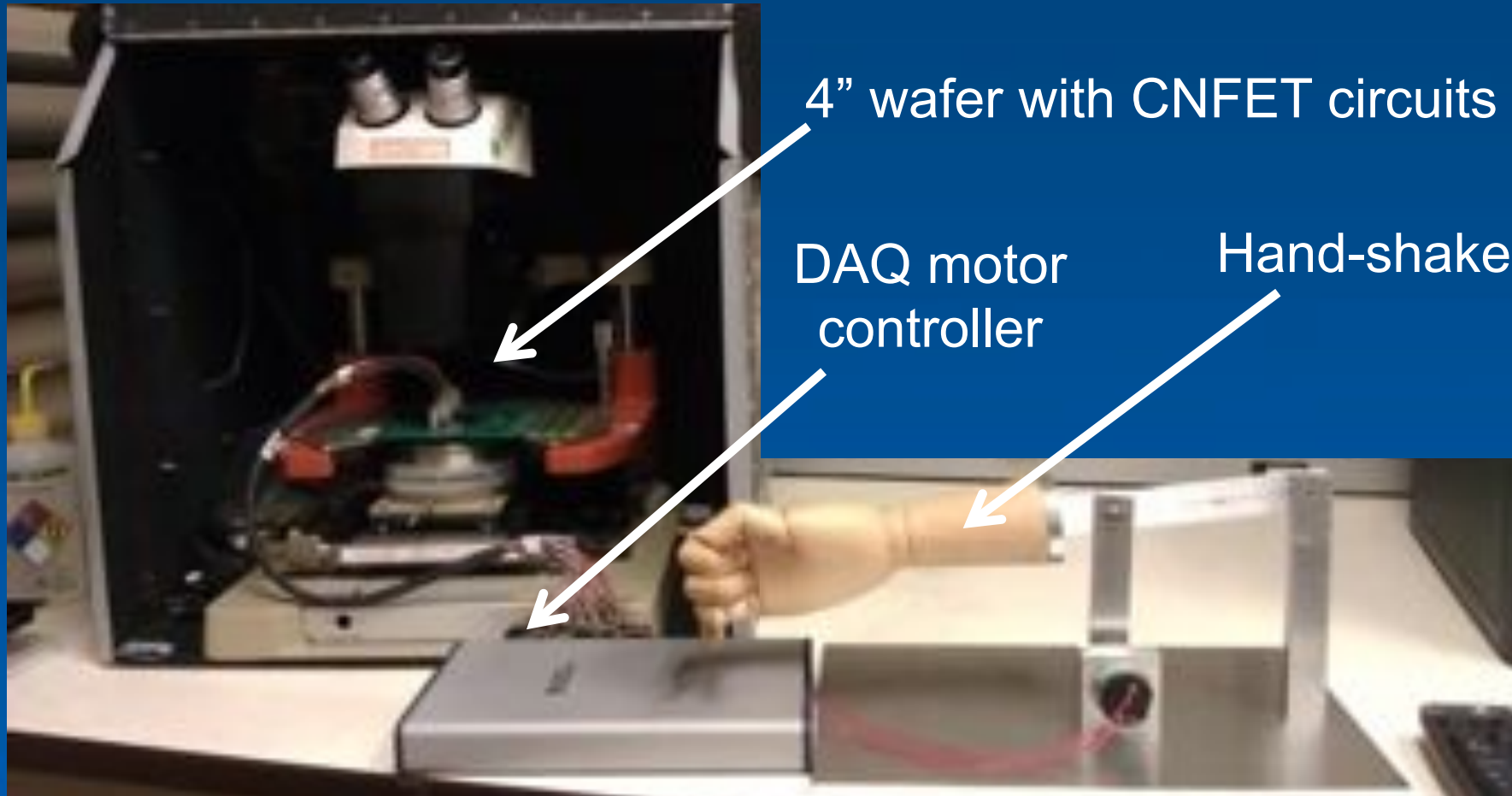


Sensor Interface Results



Sensor Interface Demonstration

Sacha: Stanford Carbon Nanotube Controlled Hand-shaker



Moving Forward

- High energy efficiency
 - CNT density
 - CNT contact resistance
 - CNT doping
- CNT variations: unique opportunities
 - CNFET correlation by layout

Conclusion

- **First demonstration**
 - sub-system built entirely using CNFETs
- **Enabled by**
 - Imperfection immune design
 - Robust CNFET processing
 - Fully digital